

# ECE-305: Spring 2018

## Exam 4 Review

Pierret, *Semiconductor Device Fundamentals* (SDF)  
MOSCAPs and MOSFETs: Chapters 15-18

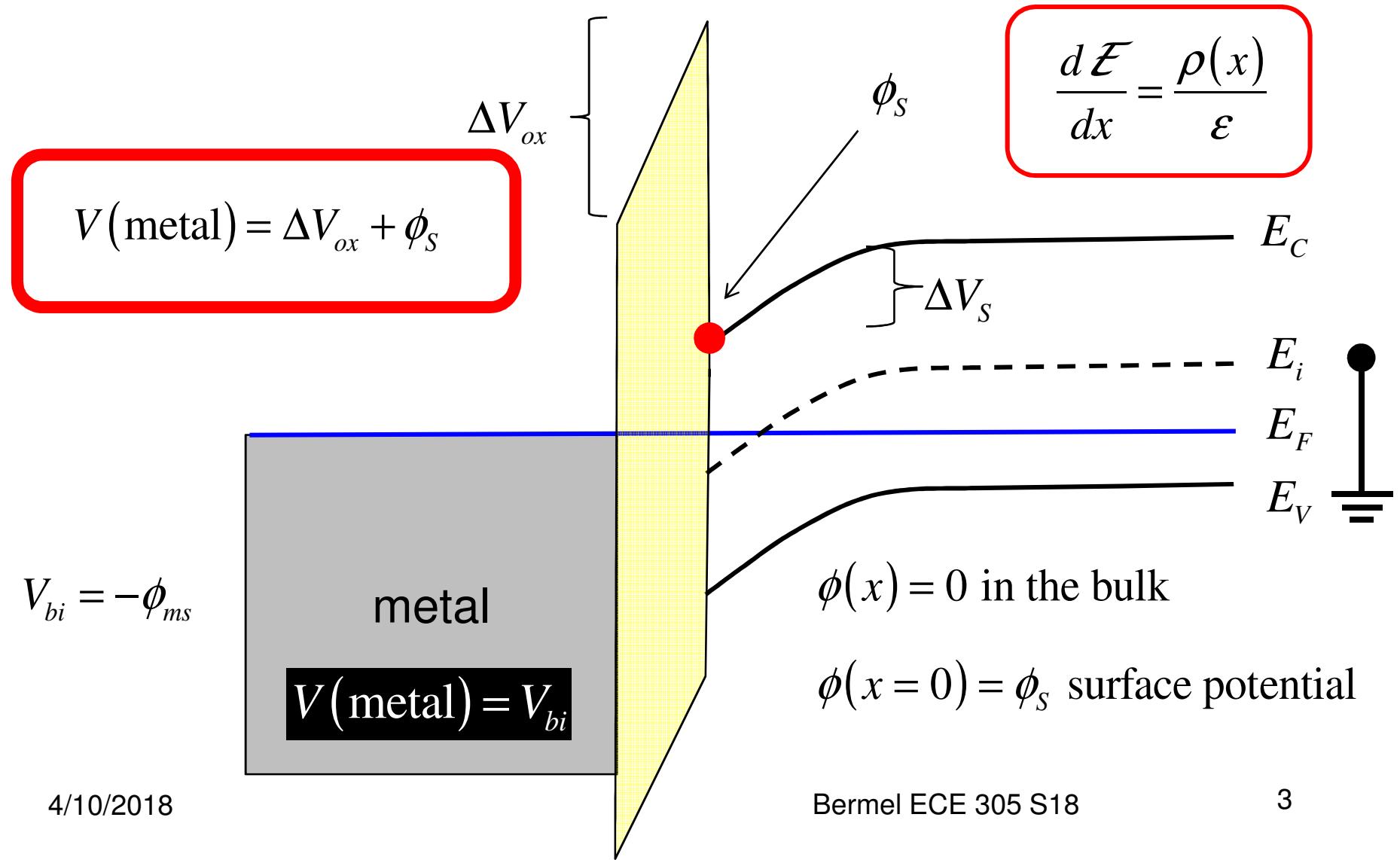
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# Key Principles in MOS devices

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- MOS geometry & band bending
- MOS junction capacitance
- MOSFET geometry
- MOSFET transfer and output characteristics
- MOSFET square law and saturation
- MOSFET reliability and variability
- MOSFET new materials

# equilibrium MOS band diagram



# band bending in p-type MOS

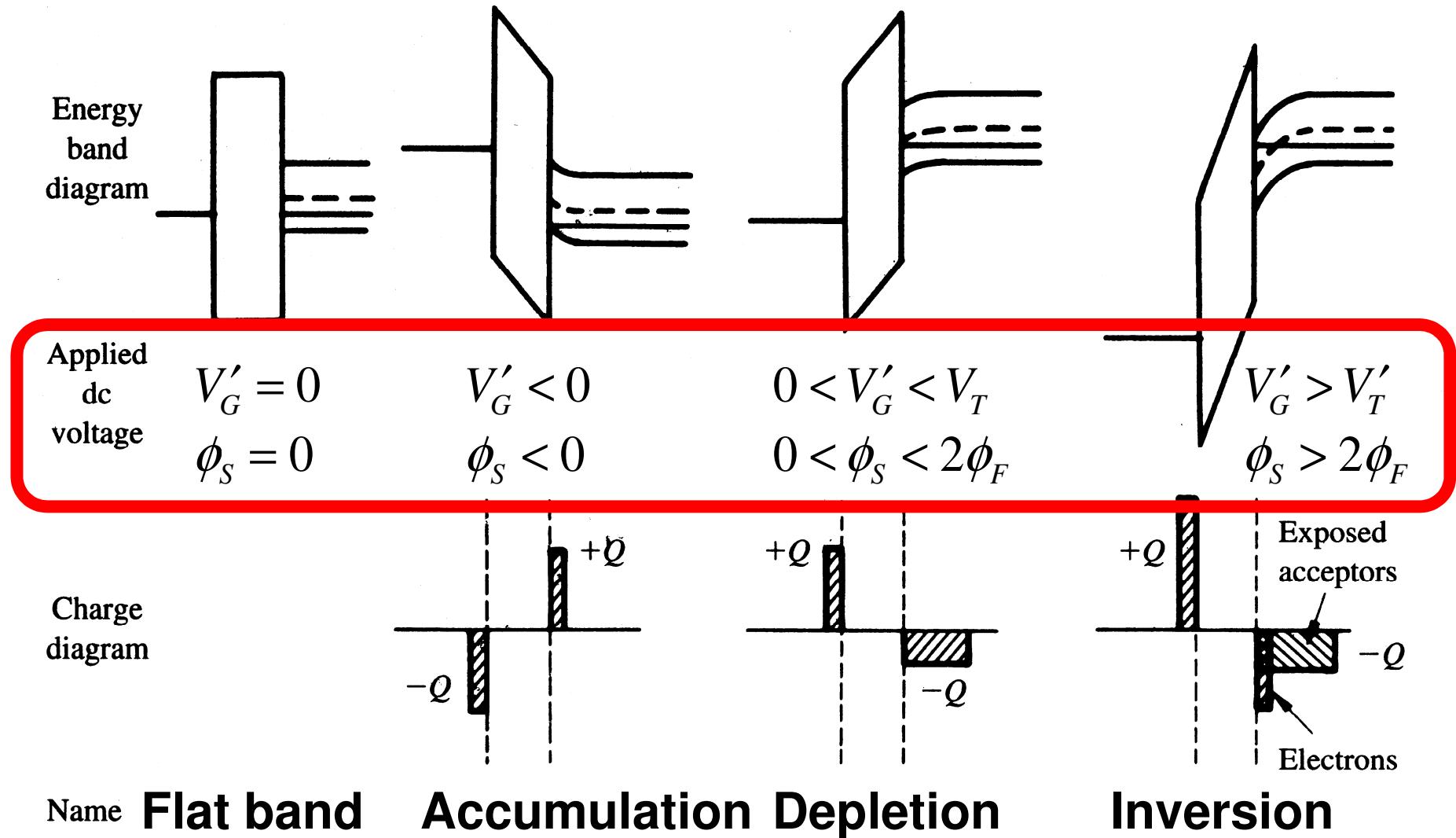
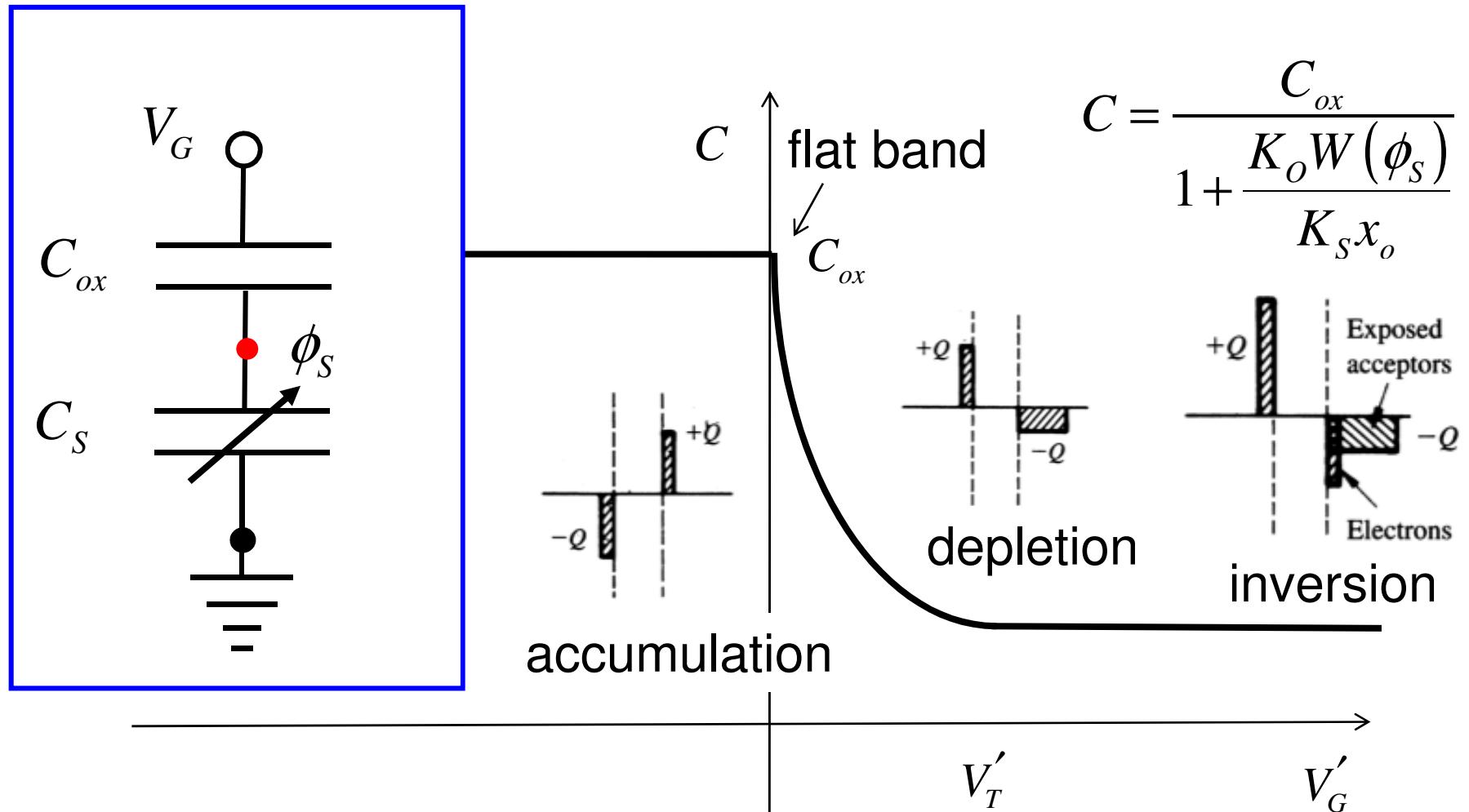
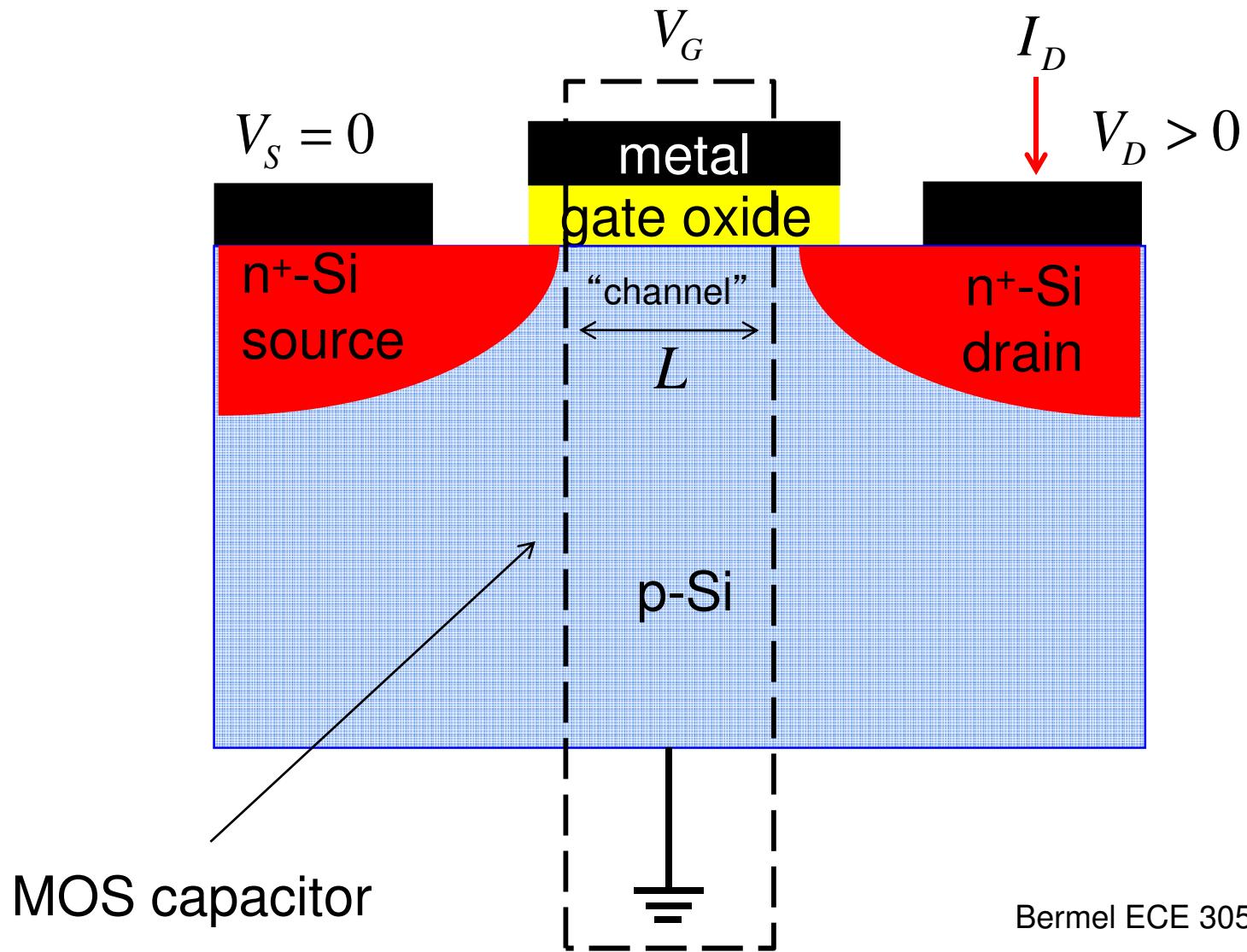


Fig. 16.6, Semiconductor Device Fundamentals, R.F. Pierret

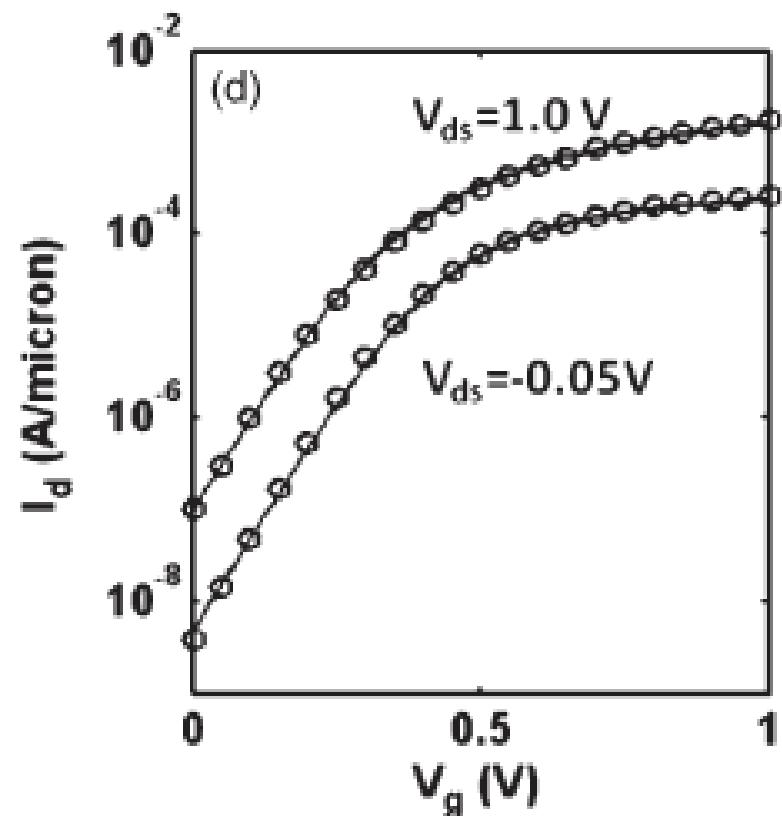
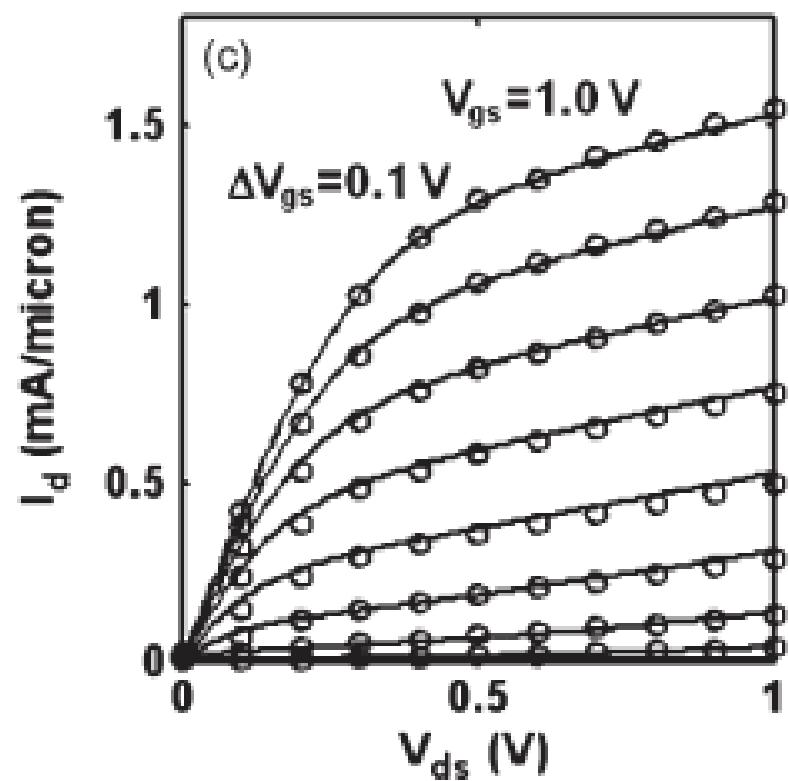
# s.s. gate capacitance vs. d.c. gate bias



# MOSFET Geometry

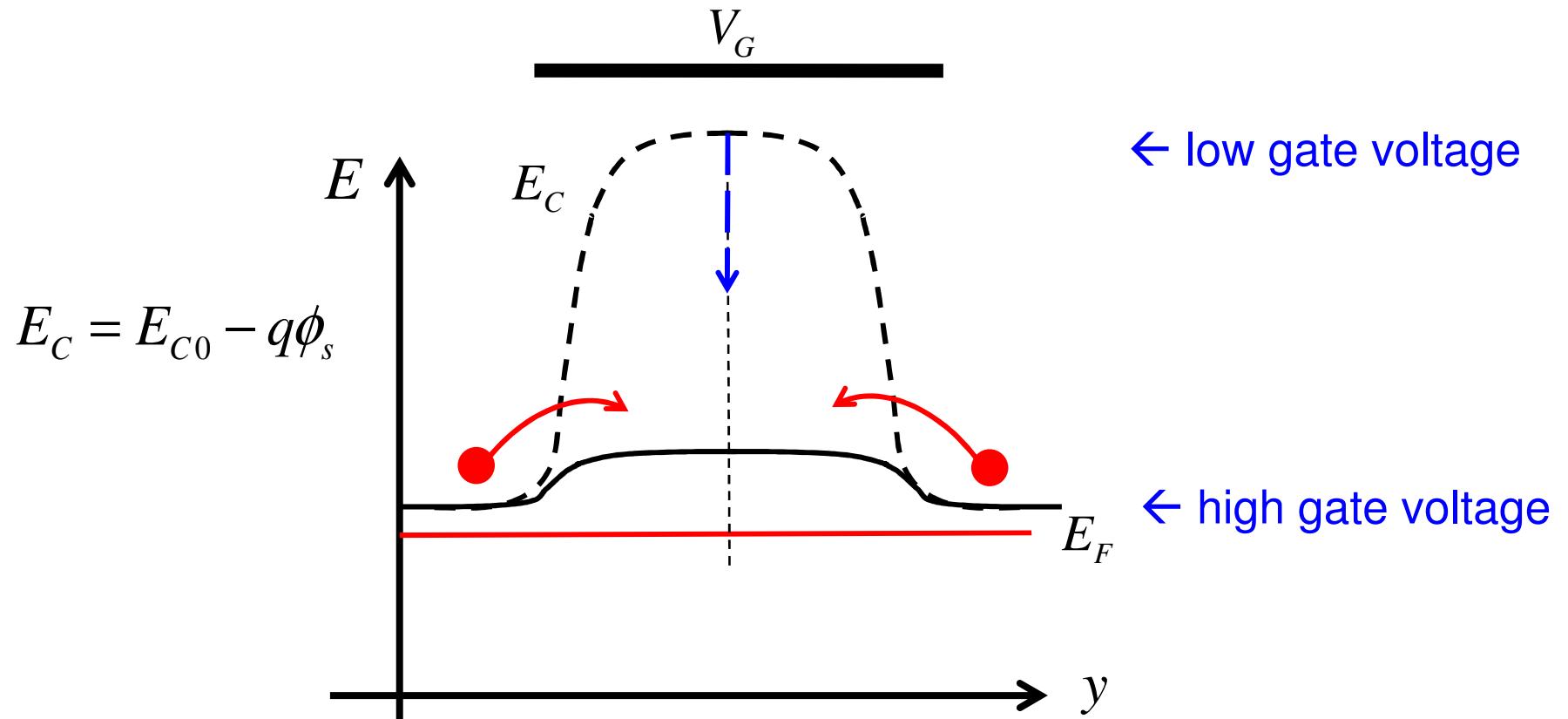


## Example: 32 nm N-MOSFET technology

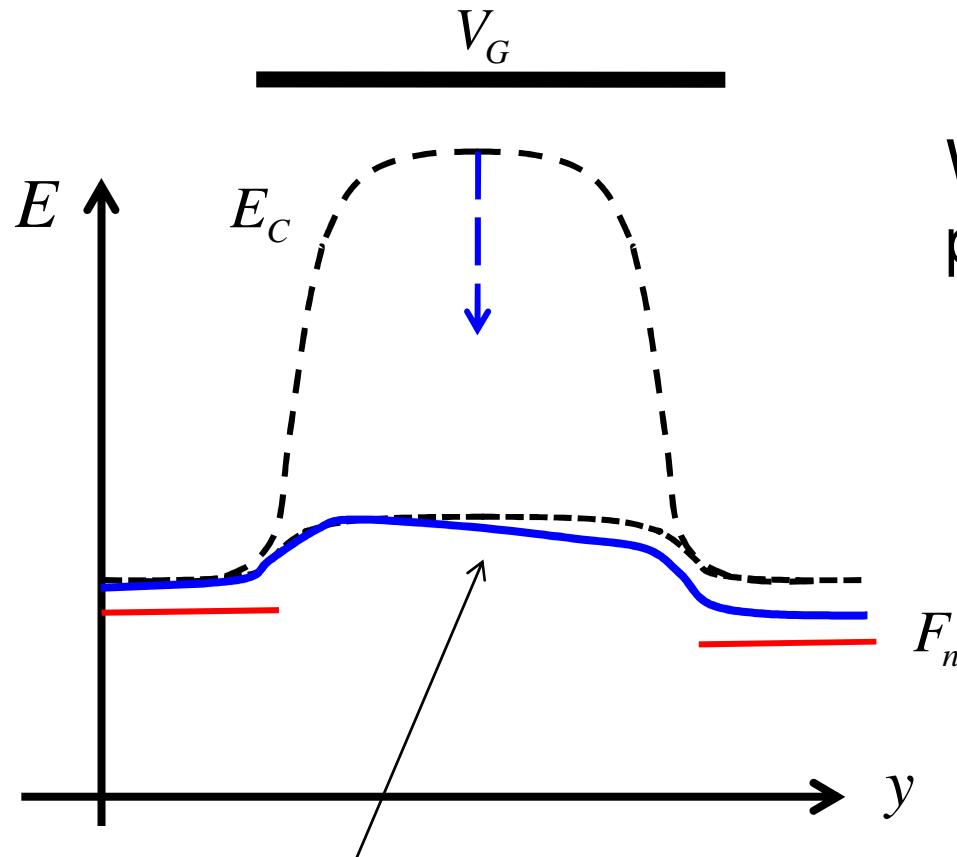


# the MOSFET is a barrier controlled device: effects of gate voltage

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# the MOSFET is a barrier controlled device: effects of a small drain voltage

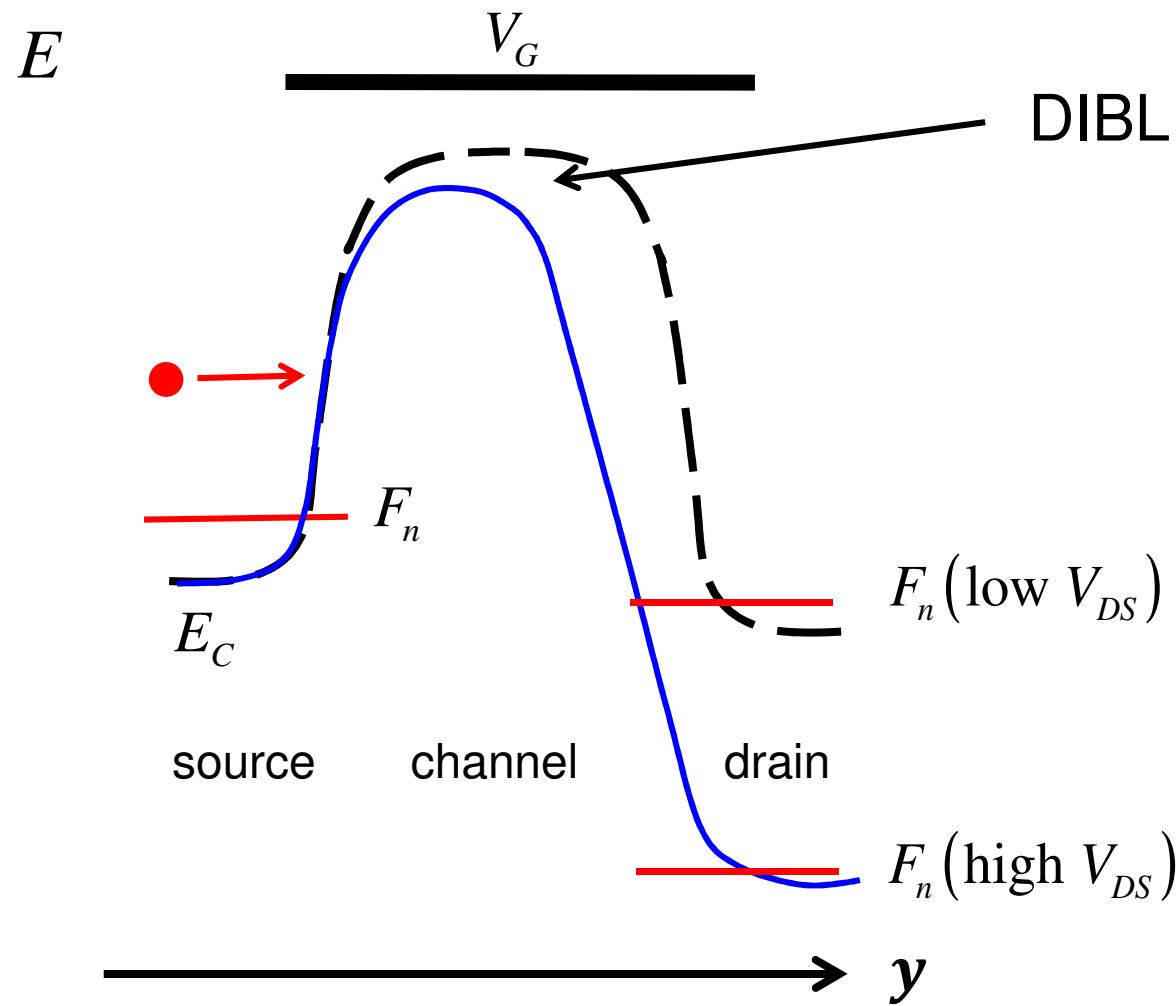


constant electric field  
substantial electron density

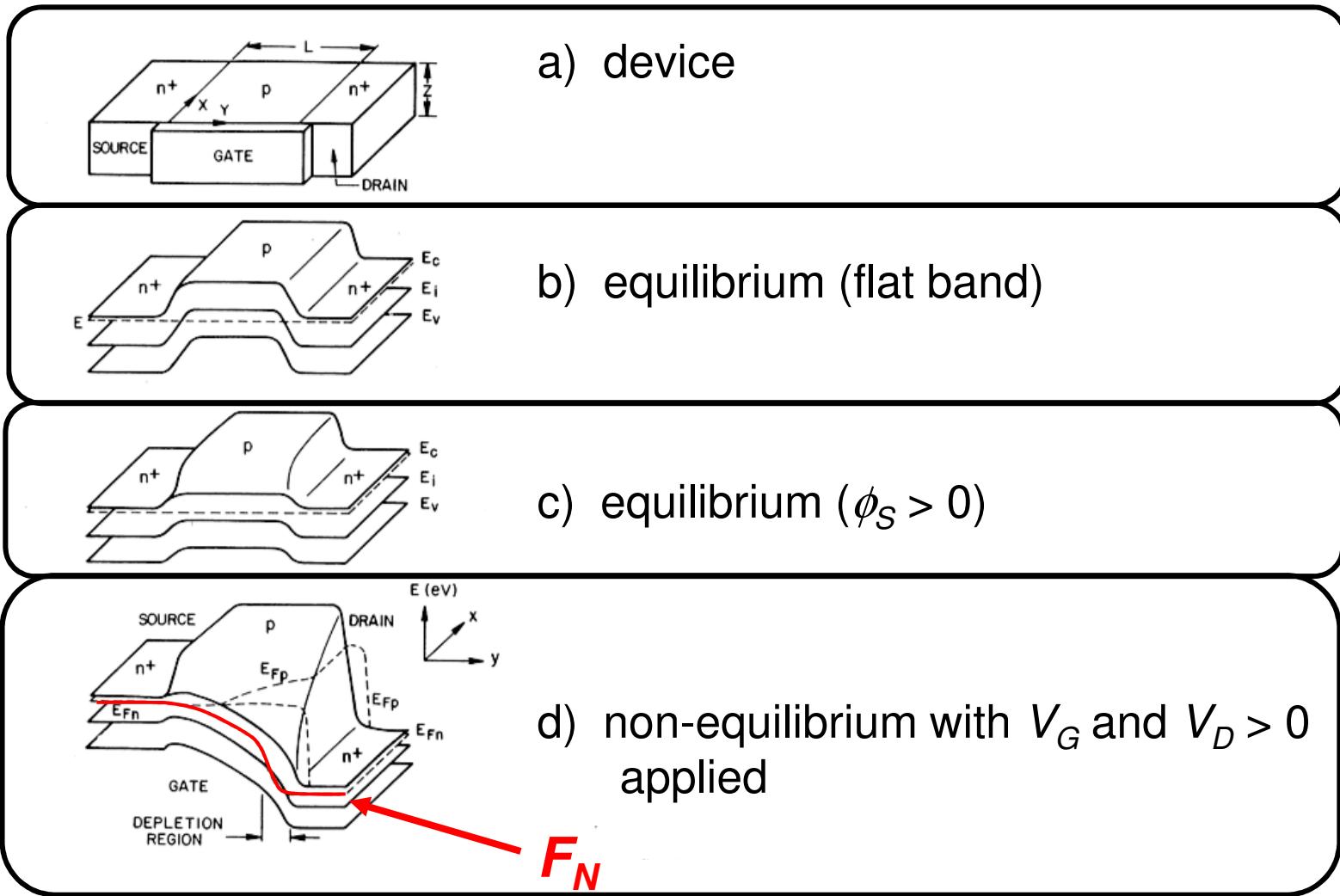
What if we apply a small positive voltage to the drain?

- 1) The Fermi level in the drain is lowered.
- 2) The conduction band is lowered too, but the electron density stays the same.

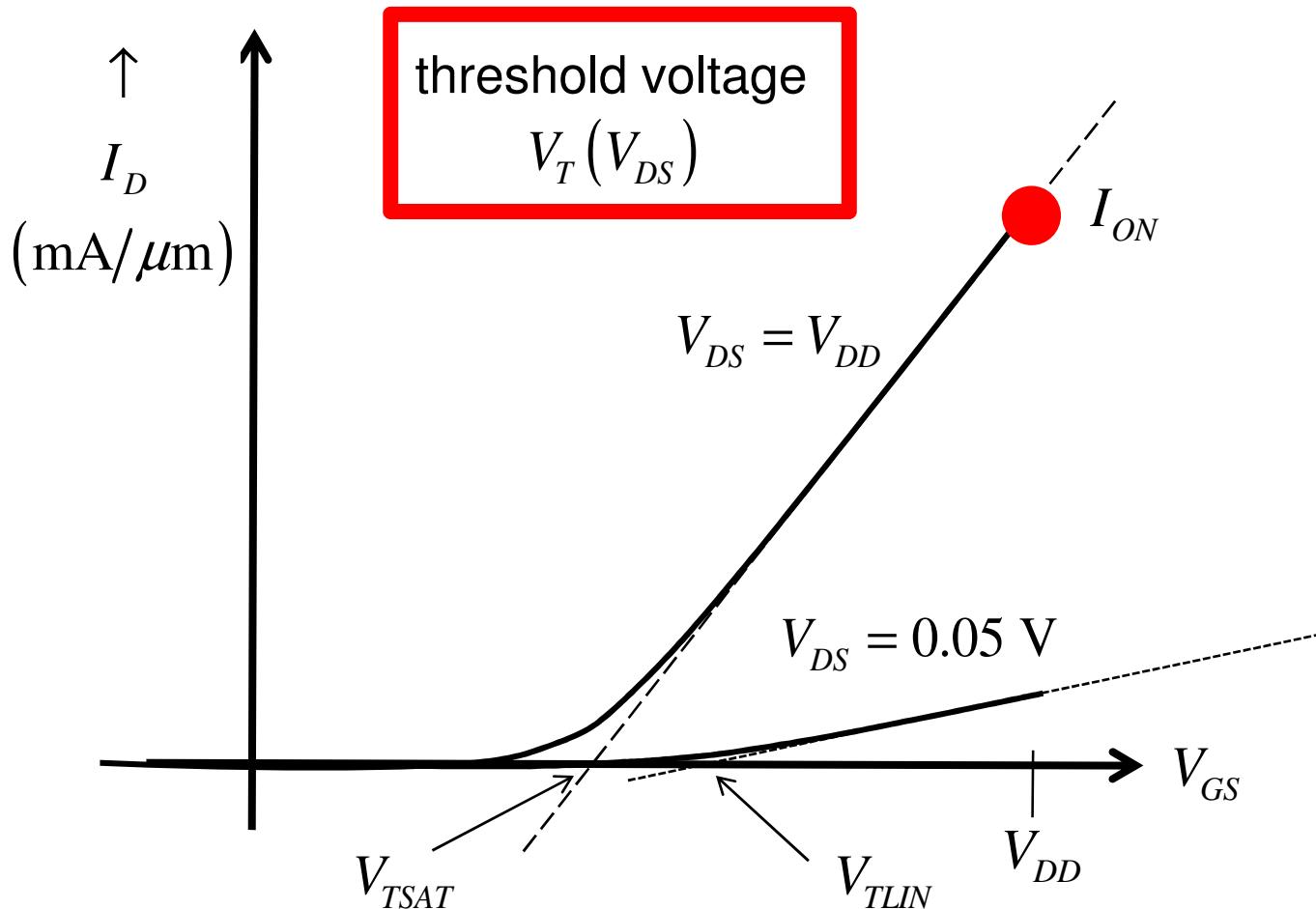
# understanding DIBL



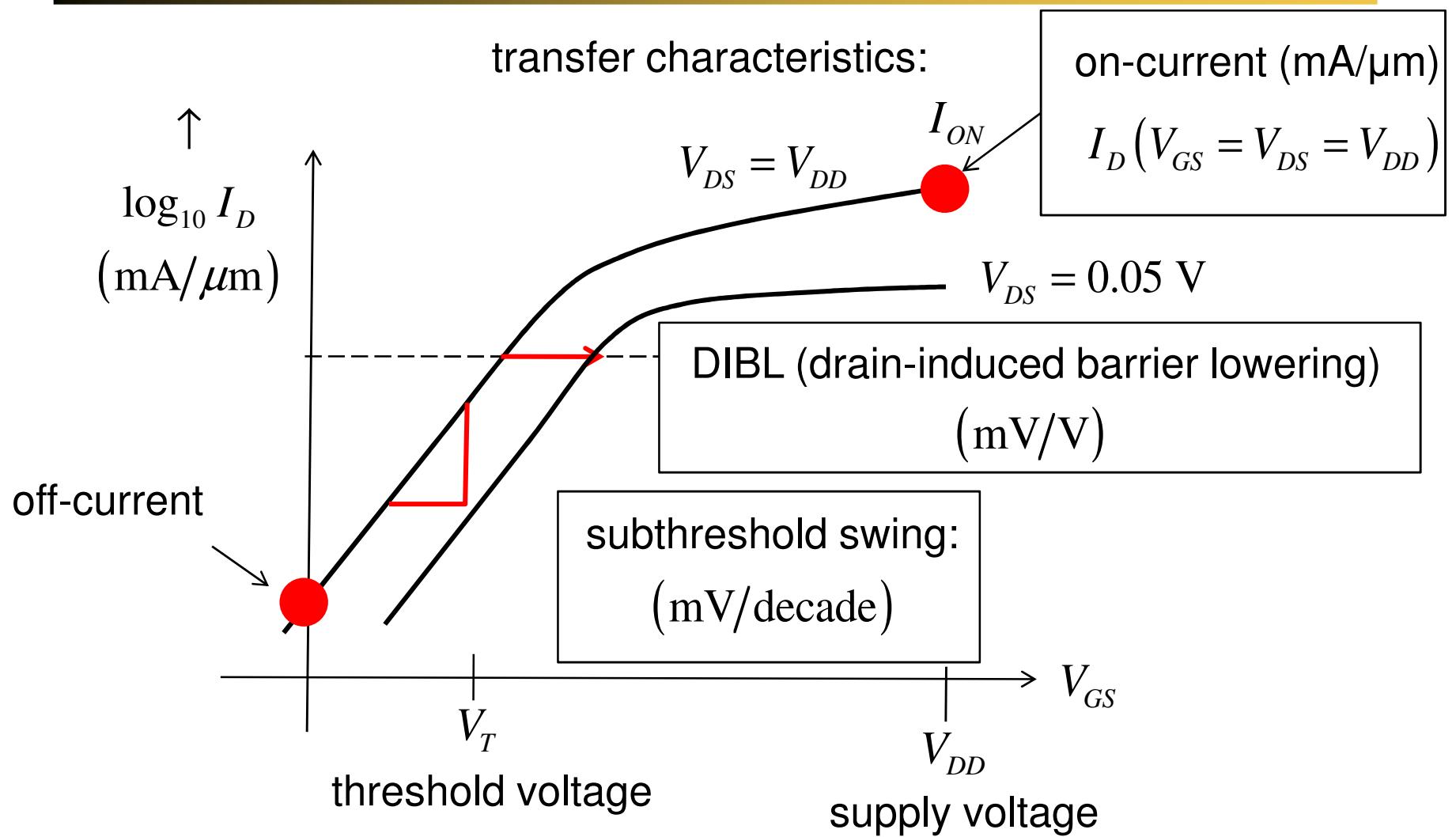
# 2D energy band diagram on n-MOSFET



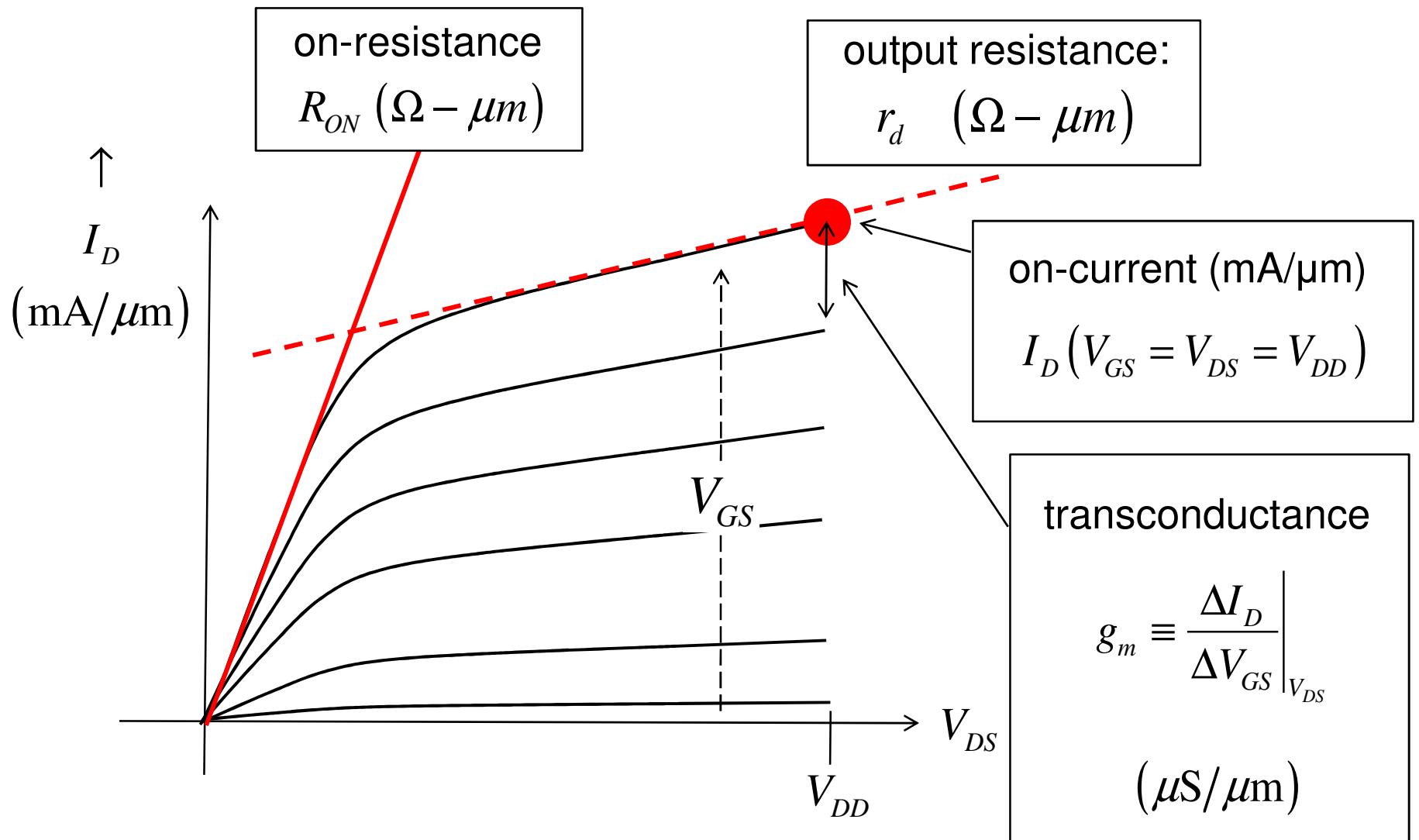
# understanding DIBL



# MOSFET device metrics



# MOSFET device metrics



# definition of body coefficient ( $m$ )

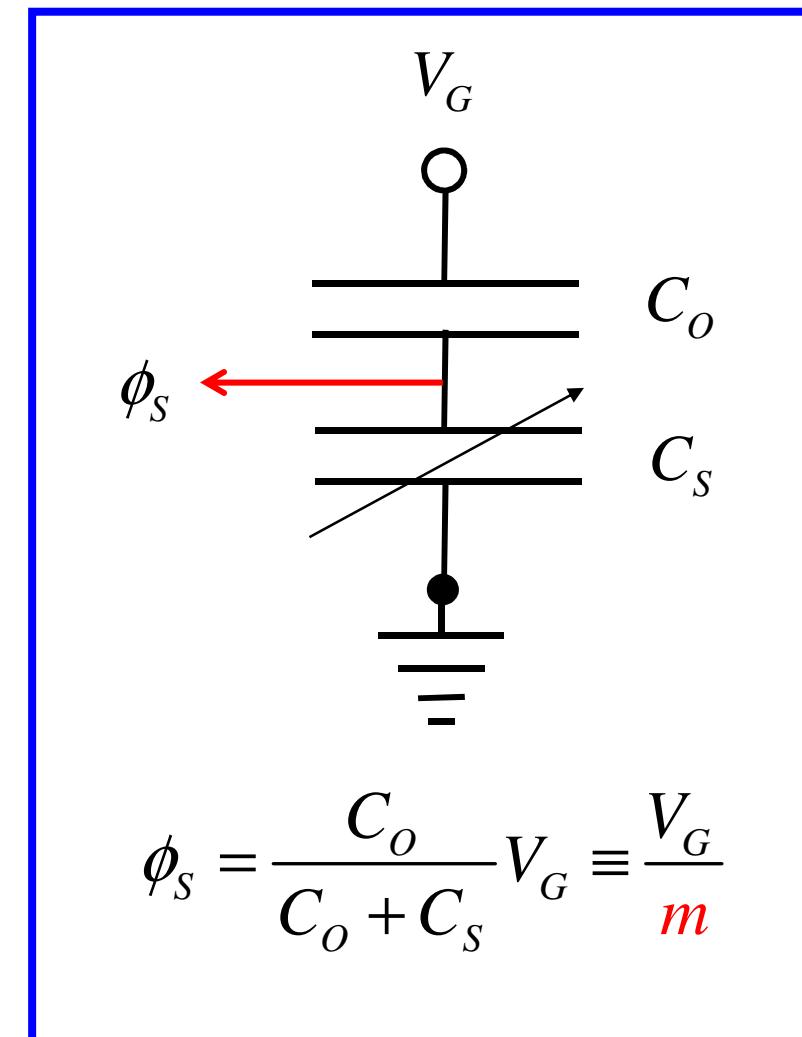
$$m \equiv (1 + C_s/C_o)$$

'Body Effect Coefficient'

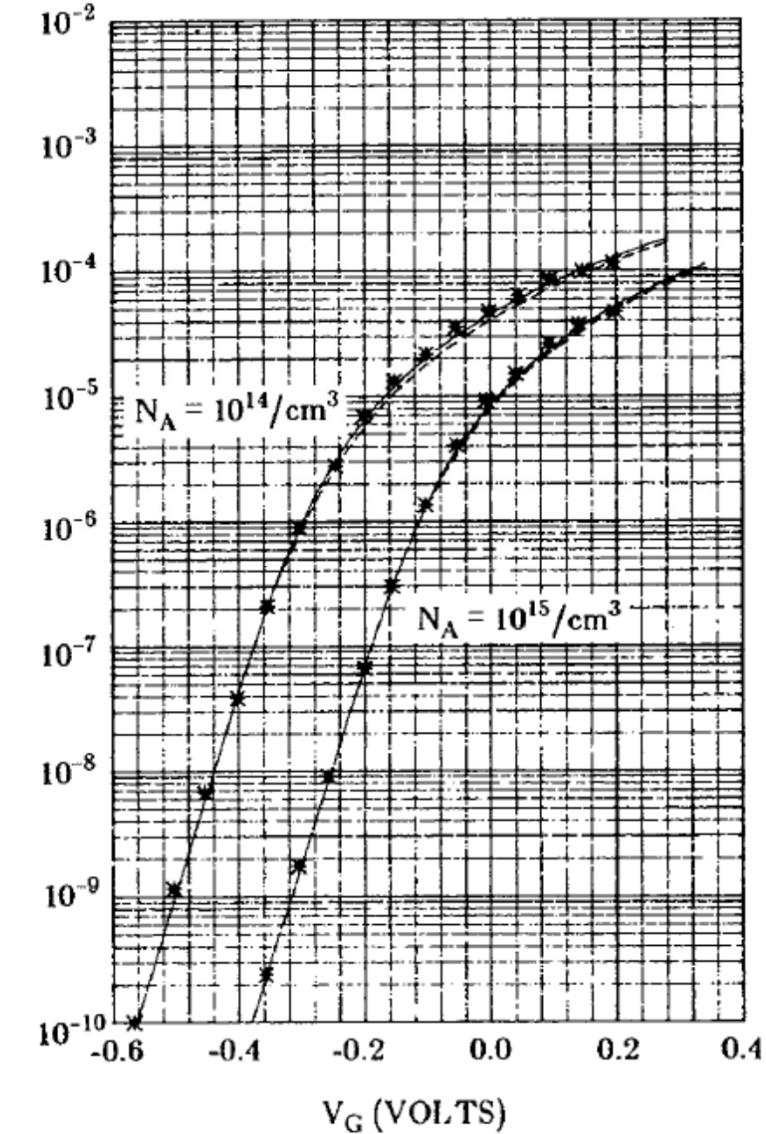
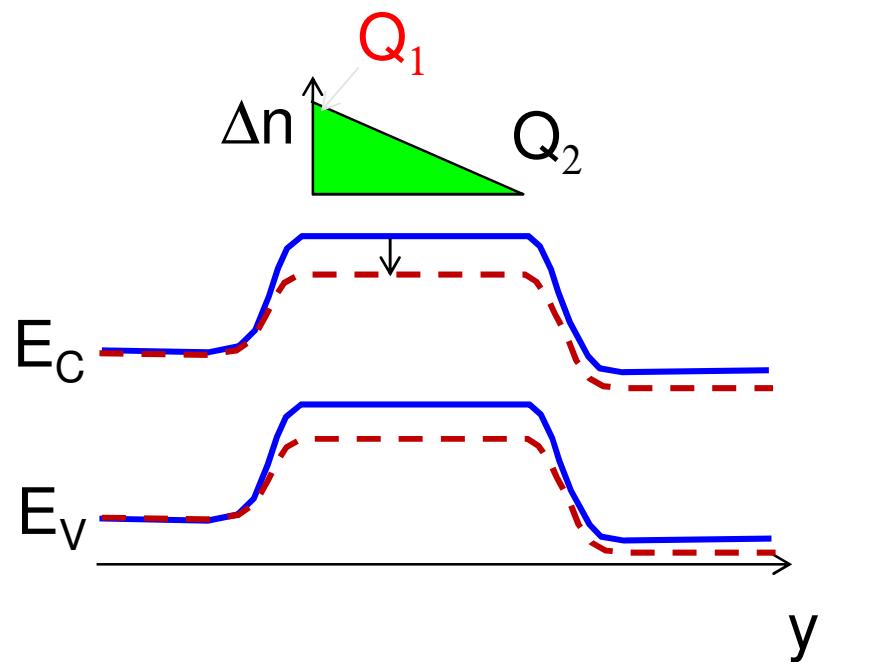
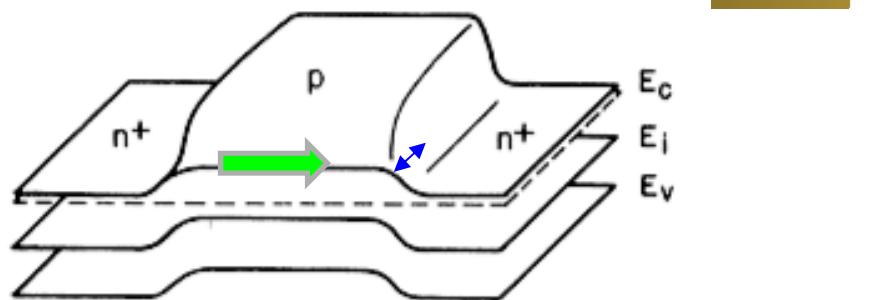
$$m = (1 + K_s x_o / K_0 W_T)$$

in practice:

$$1.1 \leq m \leq 1.4$$

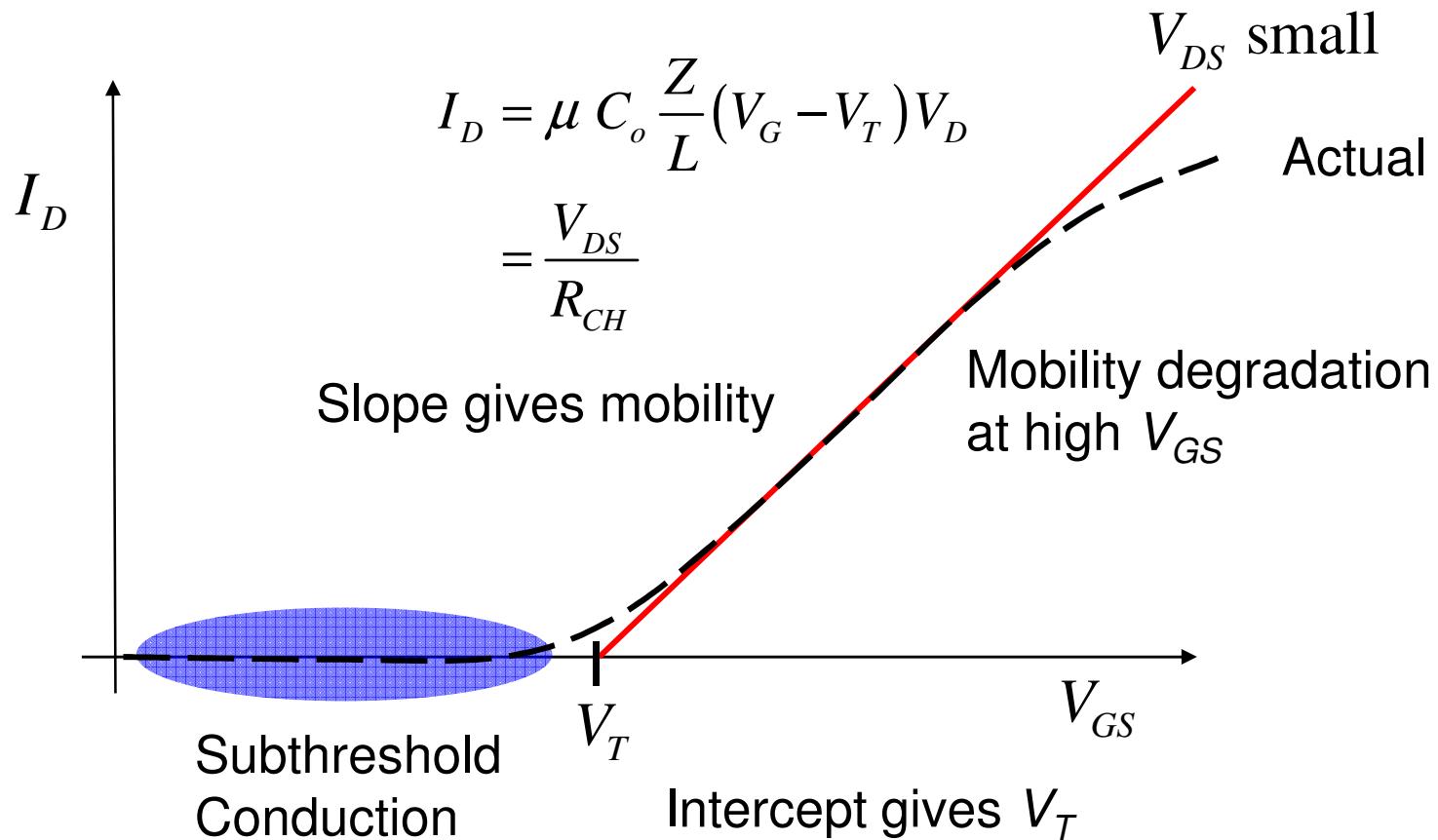


# Subthreshold Region ( $V_G < V_{th}$ )



# Linear Region (Low $V_{DS}$ )

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# Post-Threshold MOS Current ( $V_G > V_{th}$ )

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$$I_D = -\frac{W}{L_{ch}} \mu_{eff} \int_0^{V_{DS}} Q_i(V) dV$$

1) Square Law

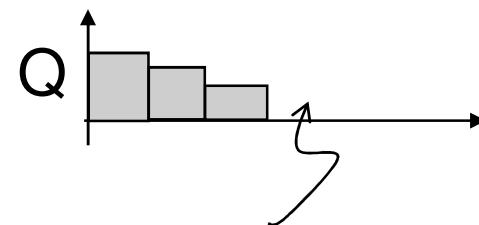
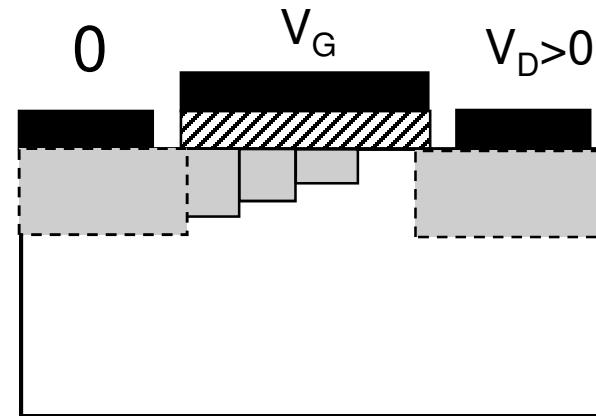
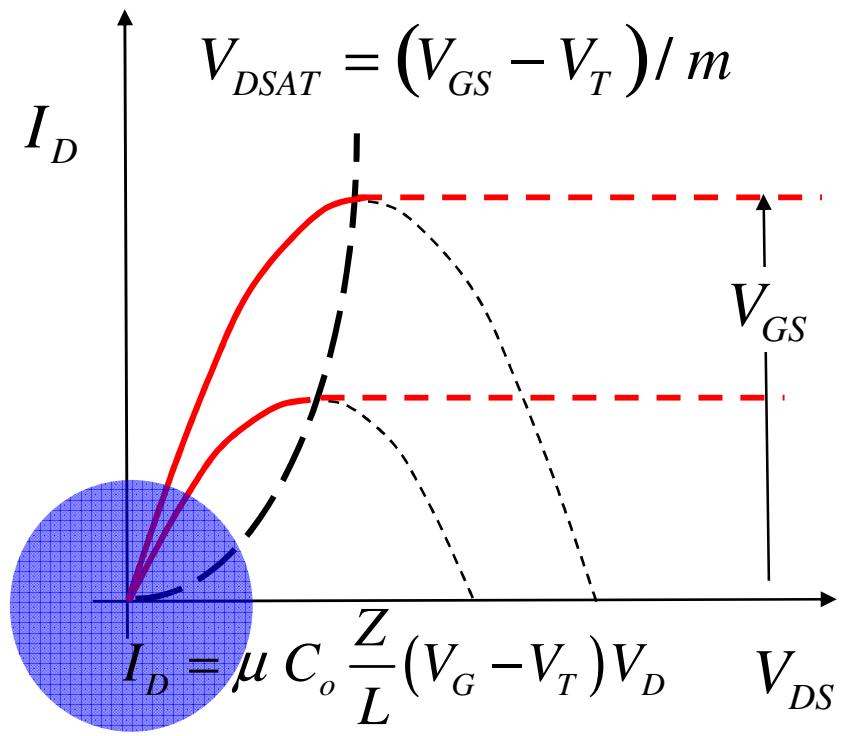
$$Q_i(V) = -C_G [V_G - V_T - V]$$

2) Simplified Bulk Charge  $Q_i(V) = -C_G [V_G - V_T - mV]$

# Why does the curve roll over?

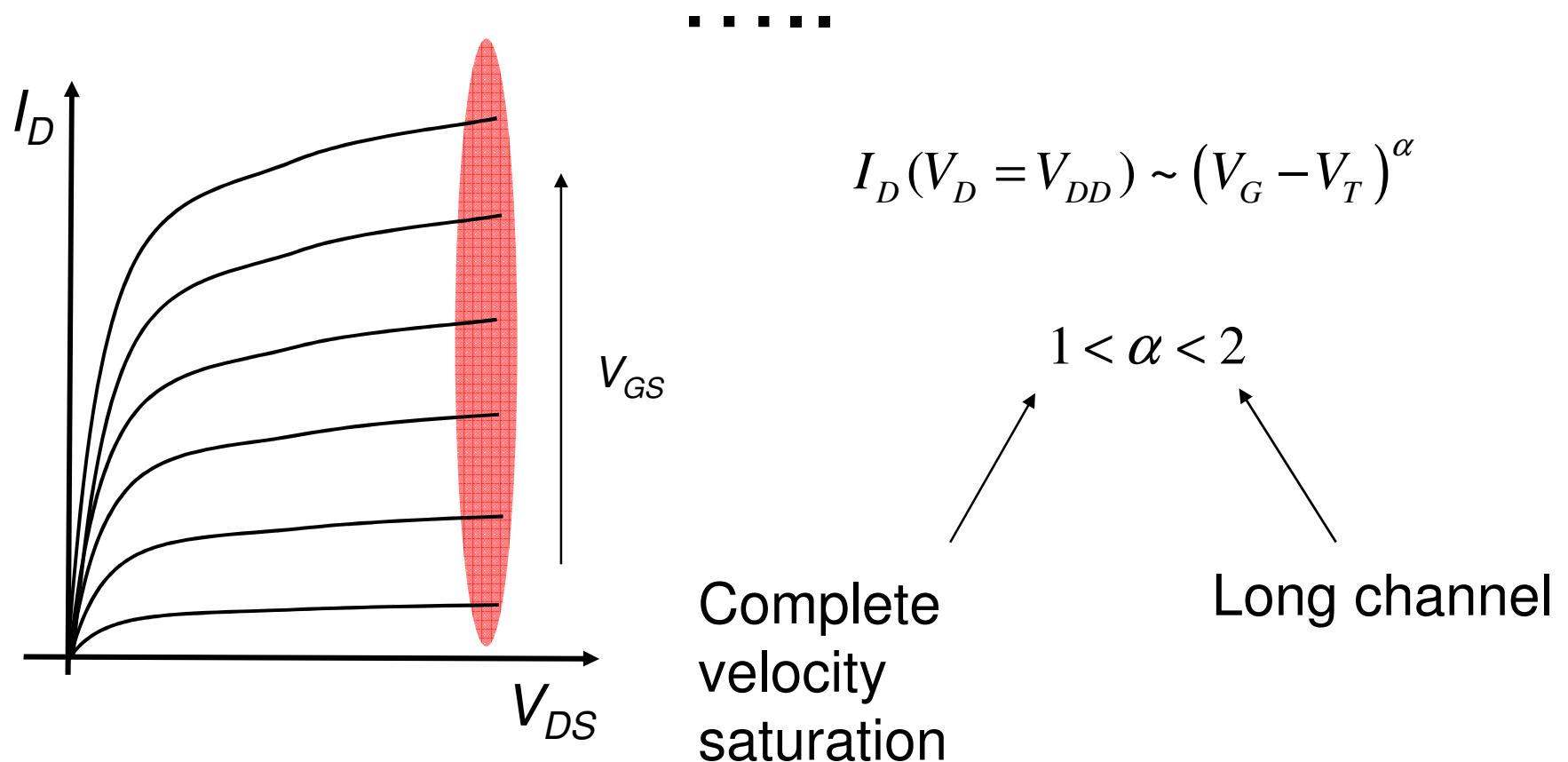
$$I_D = \frac{W\mu C_o}{2mL} (V_G - V_T)^2$$

$$Q_i \approx -C_o(V_G - V_T - mV)$$

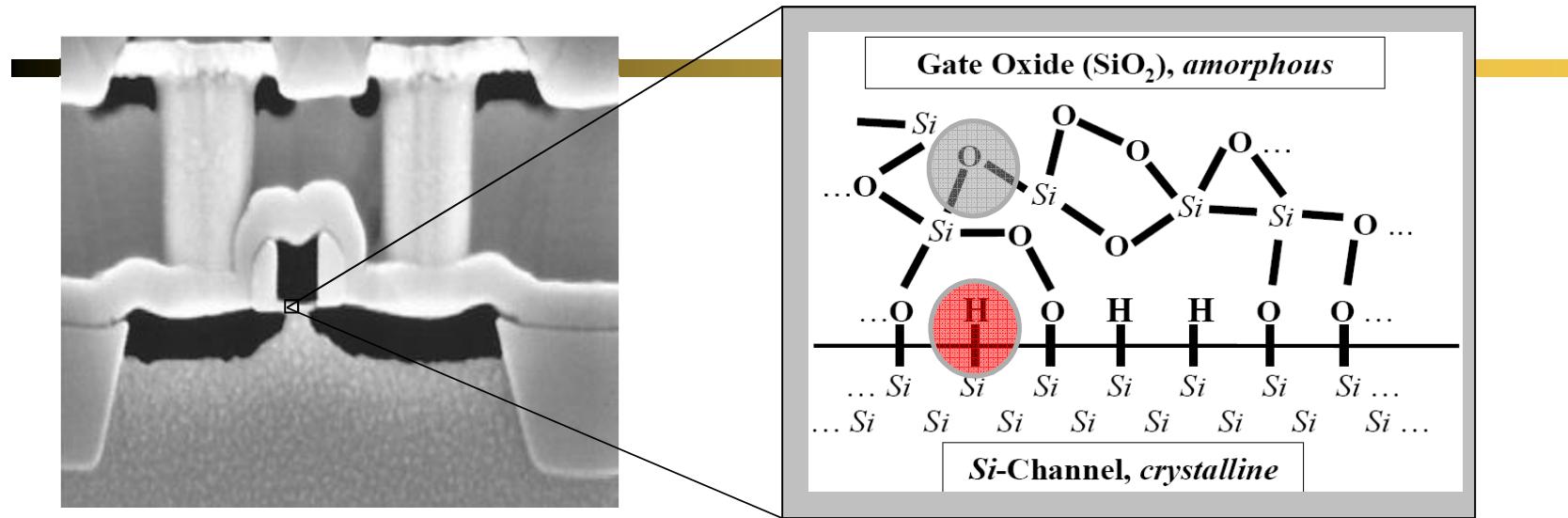


loss of inversion

# $I_D$ and $(V_{GS} - V_T)$ : In practice

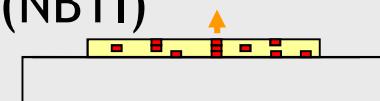


# Failure mechanisms



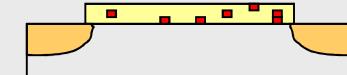
## Broken Si-H bonds

- Negative Bias Temperature Instability (NBTI)
- Hot carrier degradation (HCI)

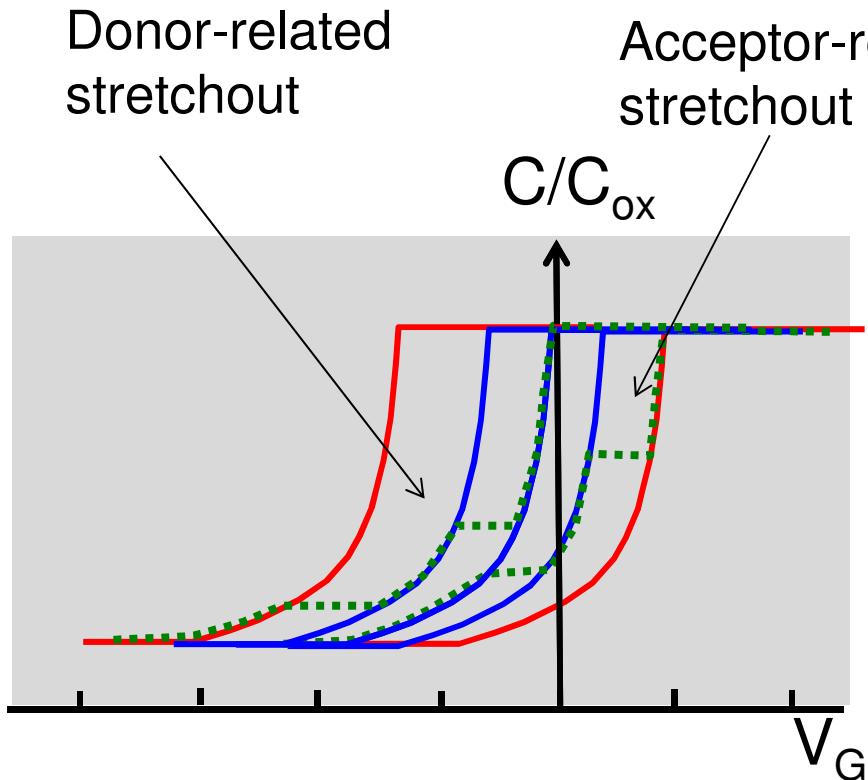


## Broken Si-O bonds

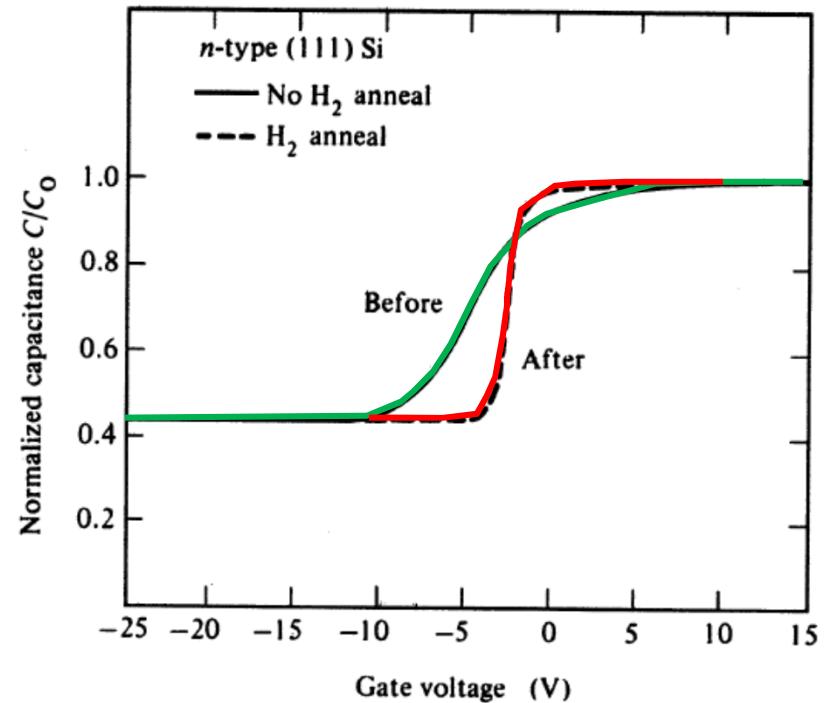
- Gate dielectric Breakdown (TDDB)
- Electrostatic Discharge (ESD)
- Radiation induced Gate Rupture (RBD)



# Threshold shifts



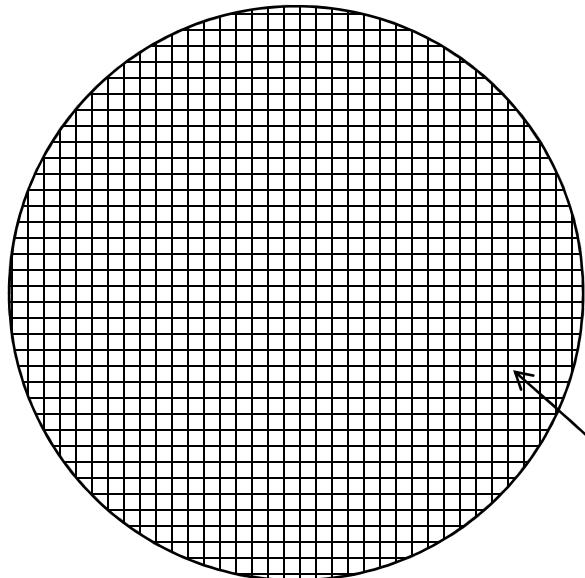
$$V_T = V_{T,ideal} - \frac{x_1}{x_o} \frac{Q_M}{C_o}$$



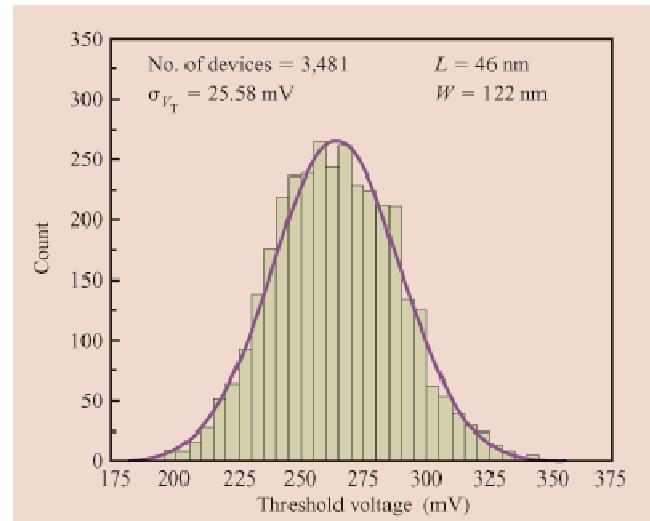
# Variability in Threshold Voltage

$$V_{th} = 2\phi_F - \frac{Q_B}{C_{ox}} = 2\phi_F + \frac{qN_A W_T}{C_{ox}}$$

$$\sigma_{V_T} = 3.19 \times 10^{-8} \left( \frac{t_{ox} N_A^{0.4}}{\sqrt{L_{\text{eff}} W_{\text{eff}}}} [\text{V}] \right),$$



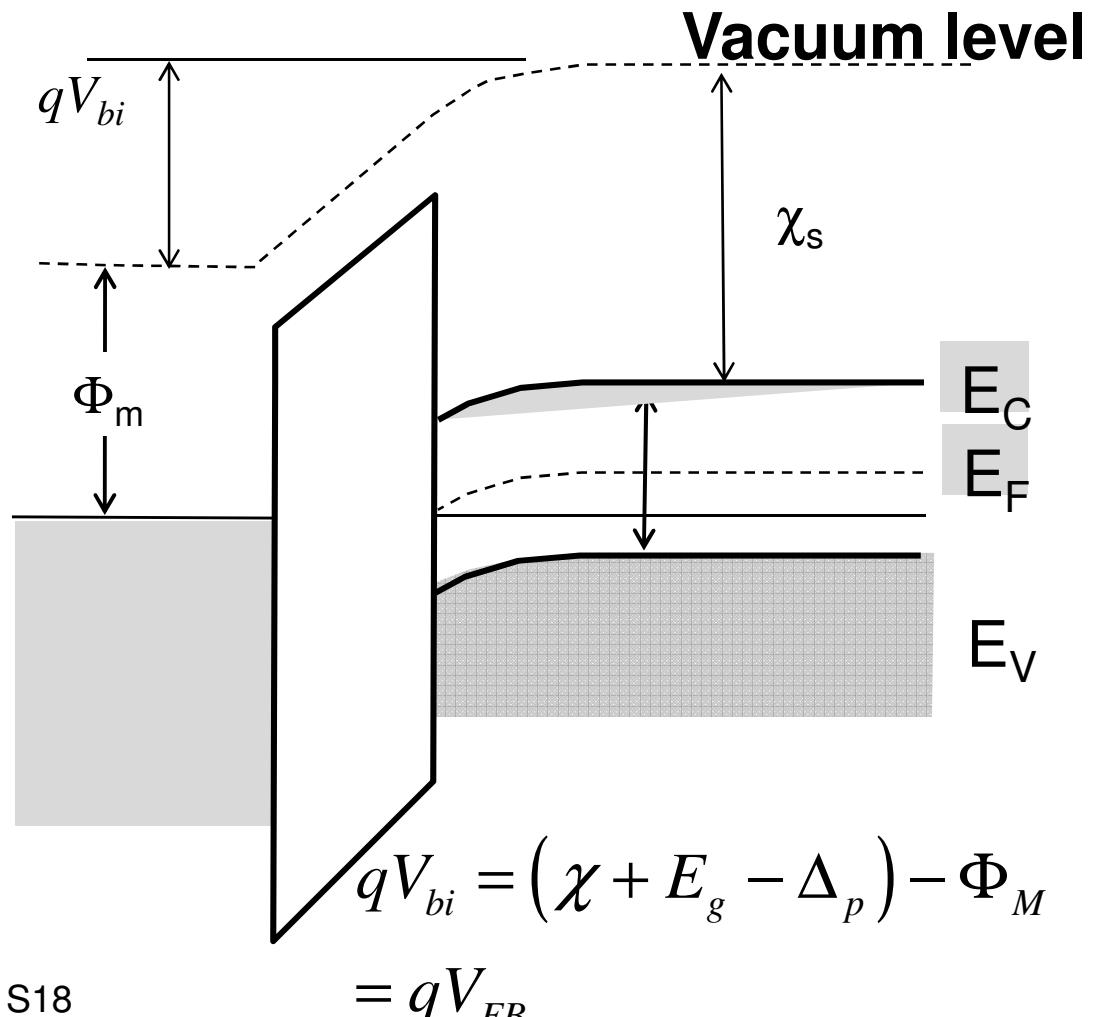
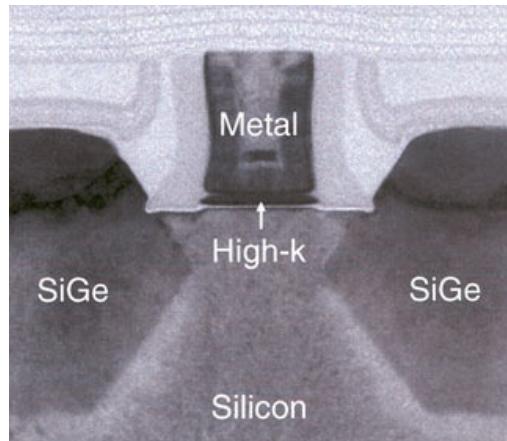
$$I_D = \frac{Z\mu C_o}{2L} (V_G - V_{T,ideal})^2$$



If every transistor has different  $V_{th}$  and therefore different current, circuit design becomes difficult

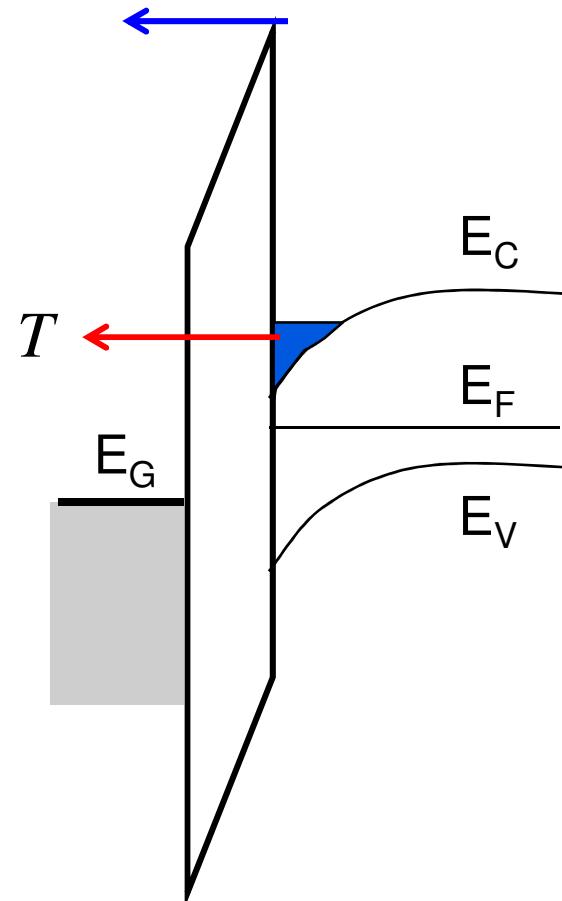
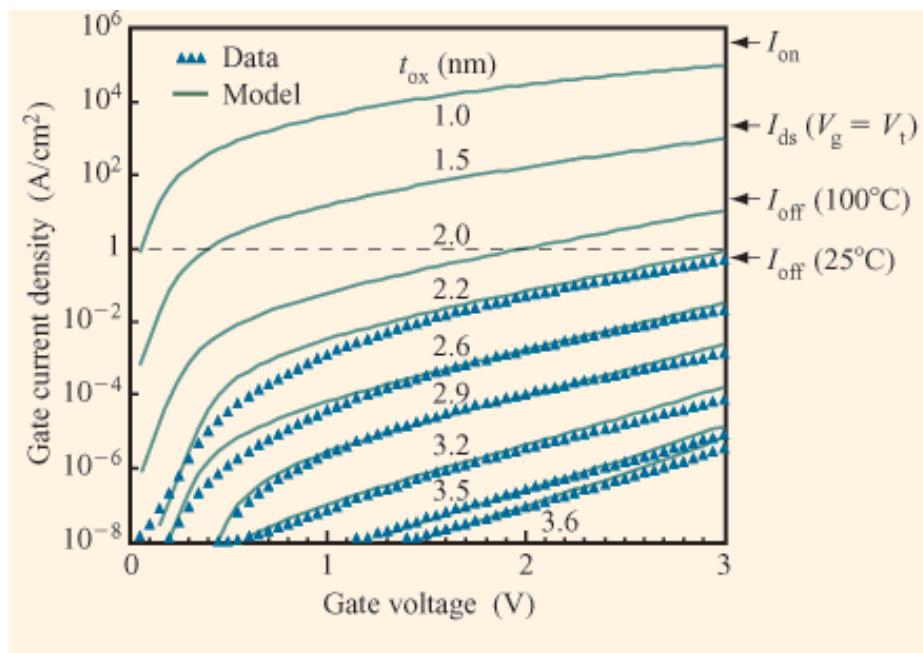
# $V_{th}$ control by Metal Work-function

## High-k/metal gate MOSFET

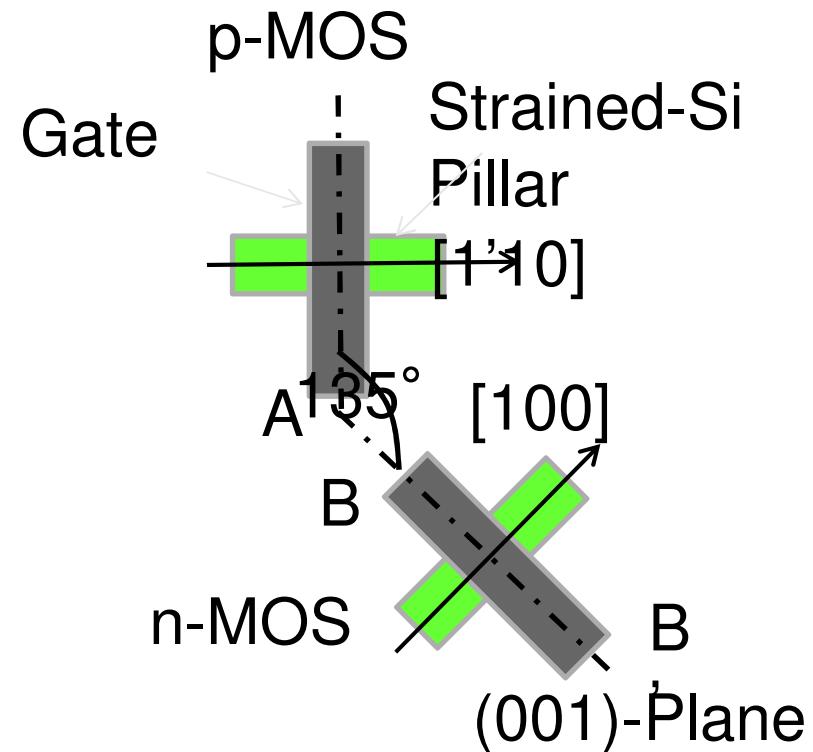
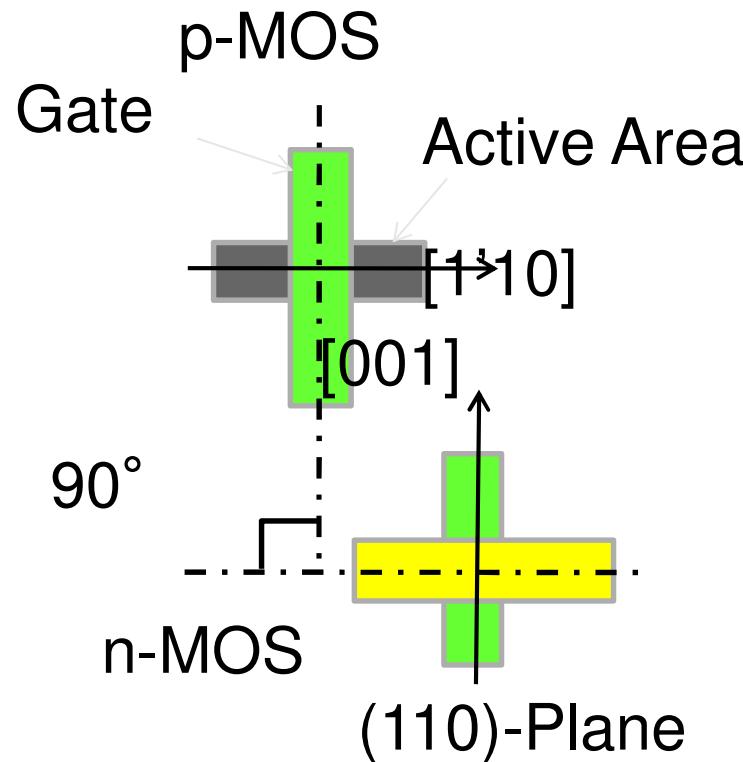


# Tunneling Current

$$J_T = \left[ Q_i(V_G) - \frac{n_i^2}{N_A} e^{-qV_G\beta} \right] v_{th} \langle T(E) \rangle$$



# Ge for PMOS, Si for NMOS

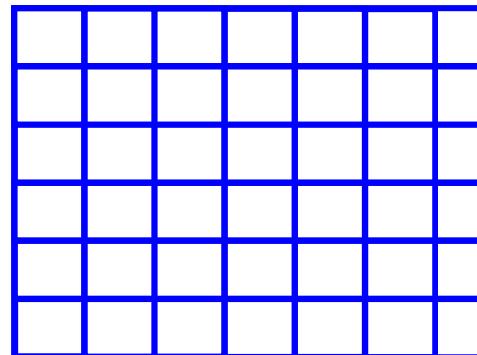
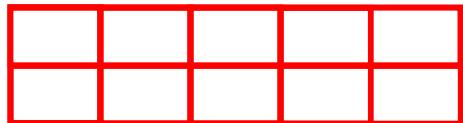


Takagi, TED 52, p.367, 2005

# Basics of Strain ..

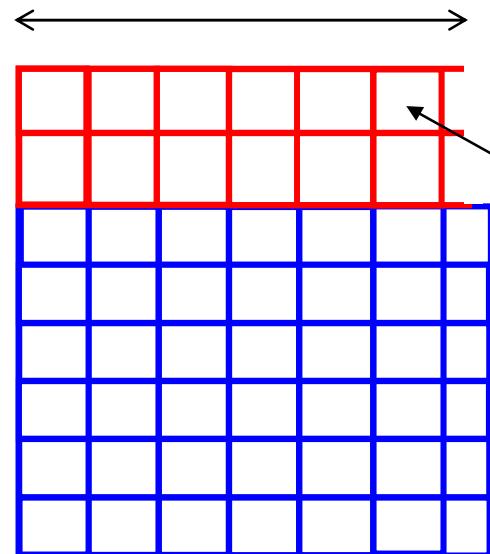
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Larger lattice



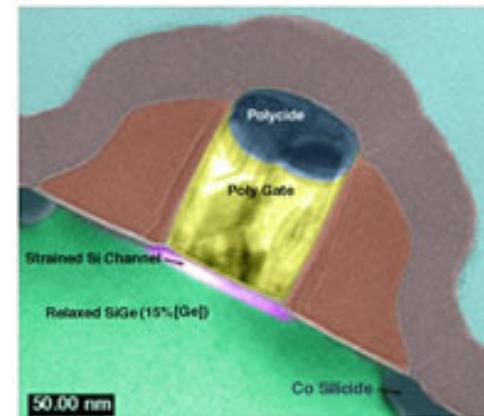
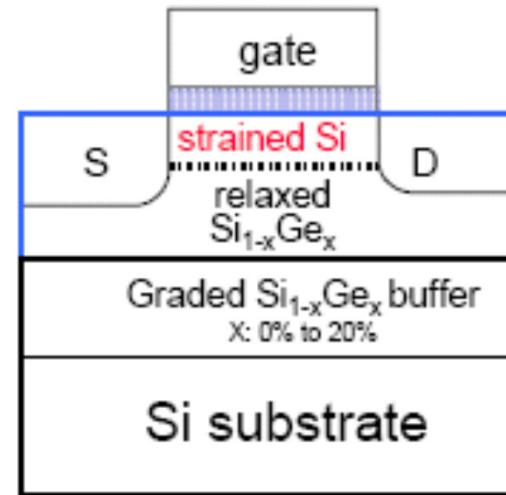
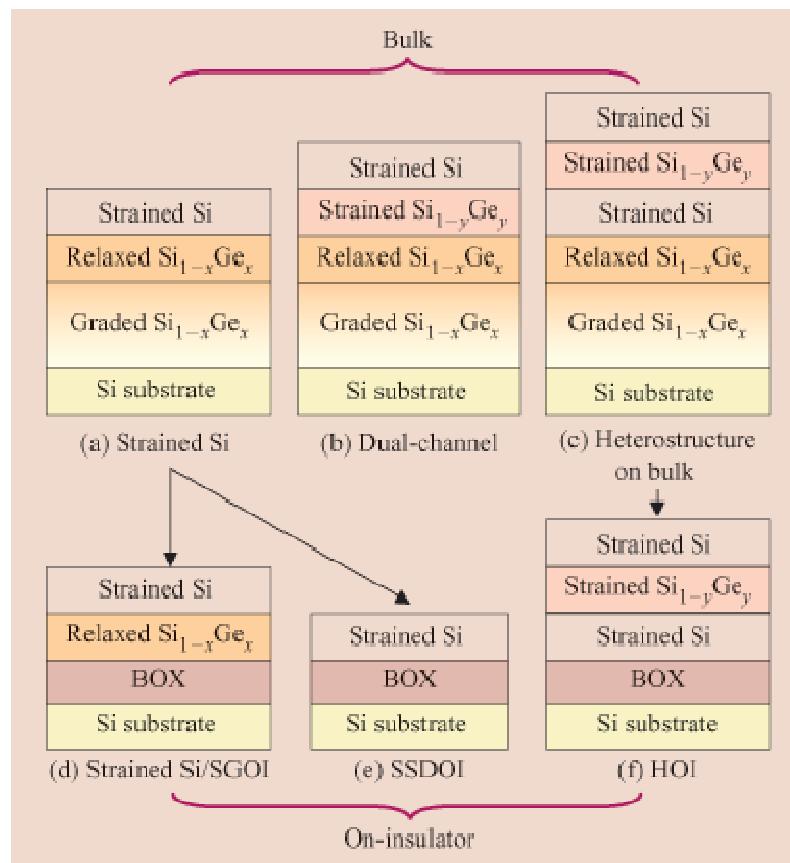
Smaller lattice

Compressive  
biaxial strain



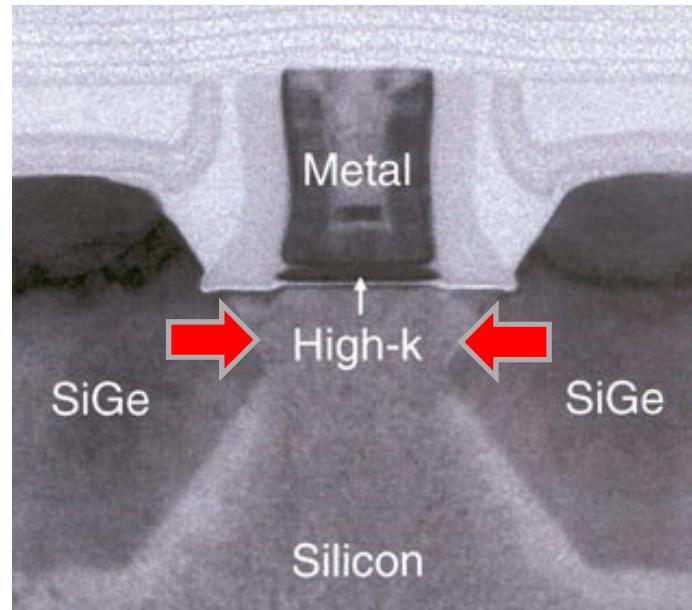
Enhances mobility  
in the channel ...

# Biaxial Strain to Enhance Mobility

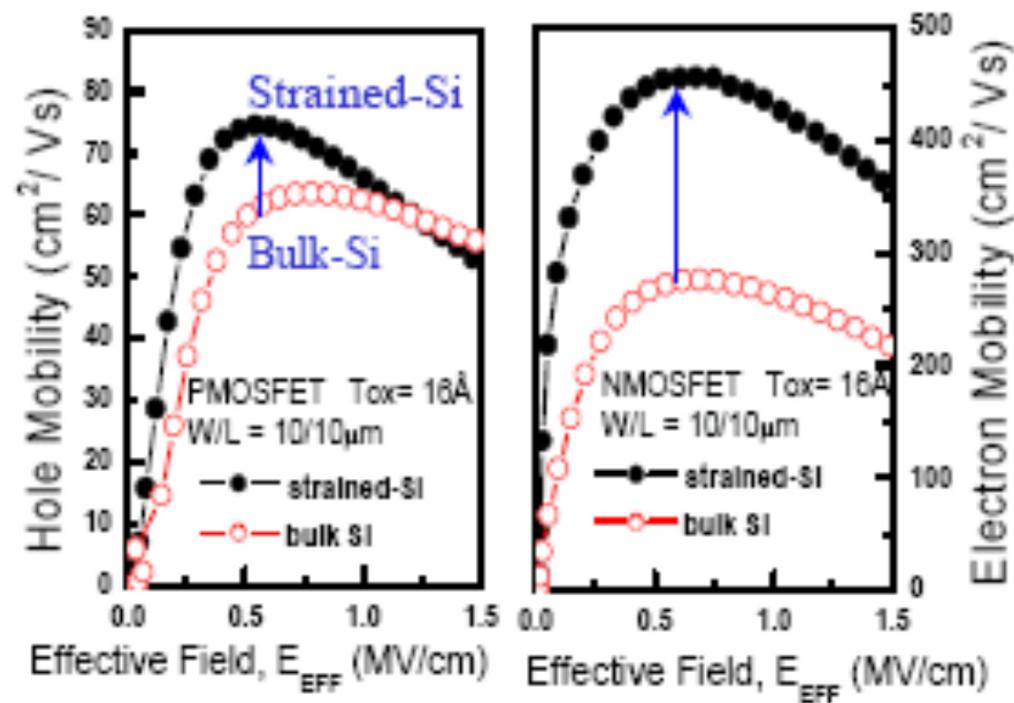
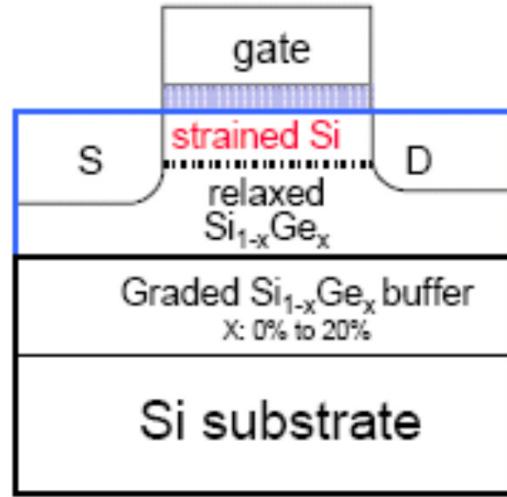


# Uniaxial Compressive Strain to Enhance Mobility

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# Biaxial Strain to Enhance Mobility



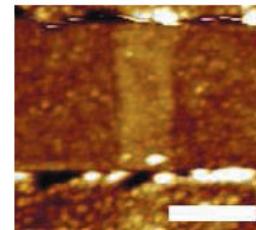
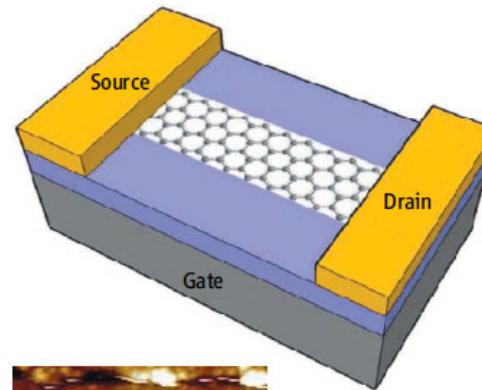
Adapted from Chang et. al, IEDM 2005

# New Channel Materials for improved mobility

	Speed of Charges in Different Materials (cm <sup>2</sup> /V·s)				
Charges	Si	GaAs	In <sub>0.53</sub> Ga <sub>0.47</sub> As	InAs	InSb
Electrons*	300	7000	10,000	15,000	30,000
Holes*	450	400	200	460	1250

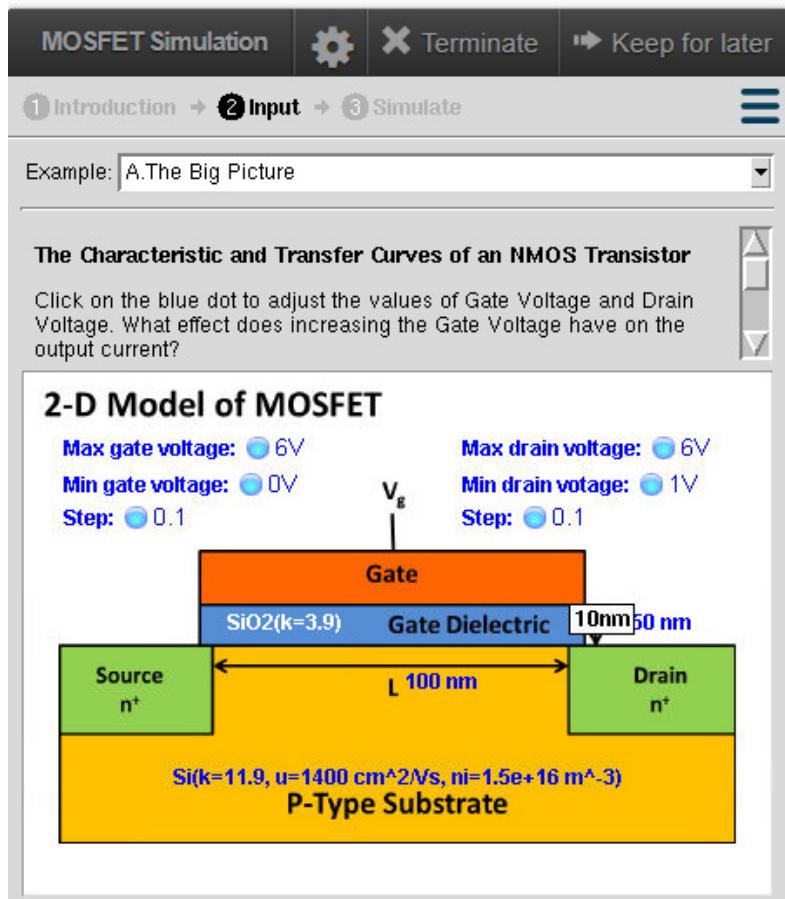
\*Electron carrier mobilities measured in transistor channels with electron concentration of  $1 \times 10^{12} \text{ cm}^{-2}$ . Hole mobilities in bulk.

Ti/Au Source	Ti/Au Gate	Ti/Au Drain
6nm p-doped		low resistance cap
10nm p-doped		Al <sub>x</sub> In <sub>1-x</sub> Sb top barrier
3nm undoped		Al <sub>x</sub> In <sub>1-x</sub> Sb top barrier
Be $\delta$ -doping		
7nm undoped		Al <sub>x</sub> In <sub>1-x</sub> Sb top spacer
5nm InSb quantum well		
3 $\mu$ m undoped Al <sub>x</sub> In <sub>1-x</sub> Sb bottom barrier		
200nm AlyIn <sub>1-y</sub> Sb interfacial layer		
Semi-insulating GaAs substrate		



New kid. Transistors made from graphene nanoribbons could be blinding fast. But can they perform on an industrial scale?

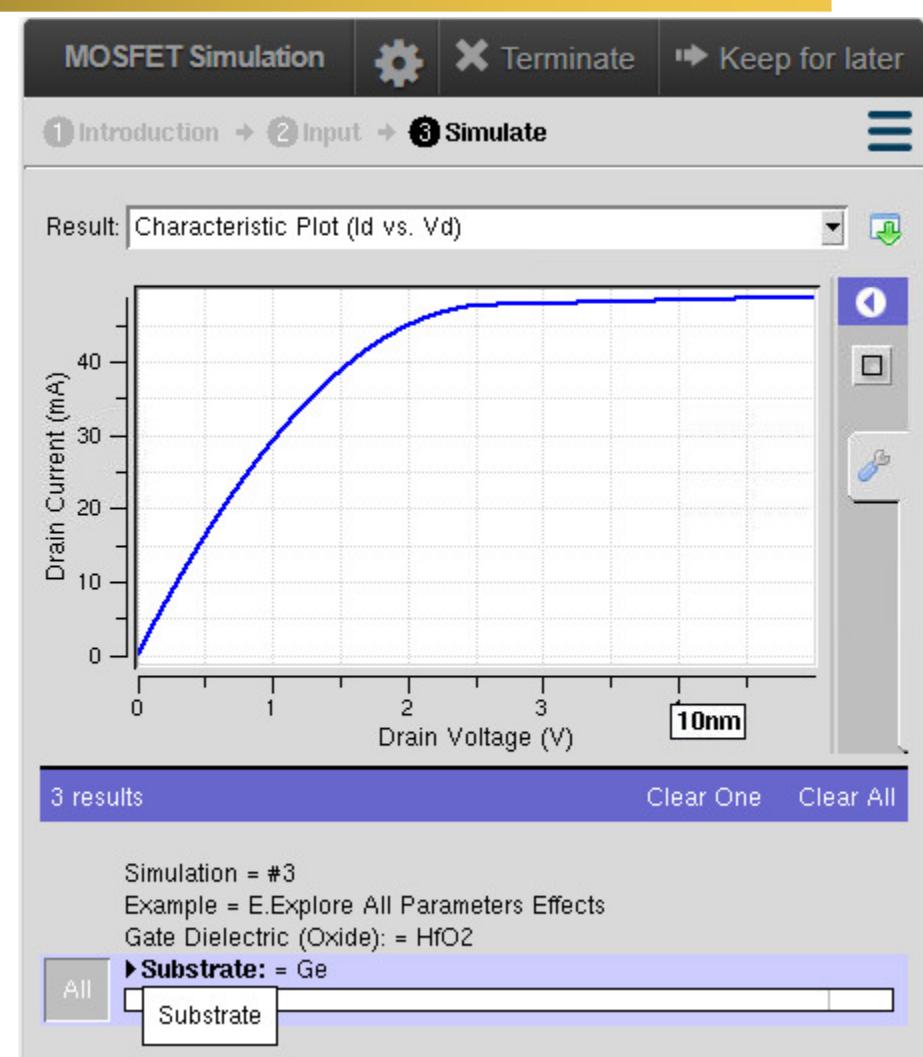
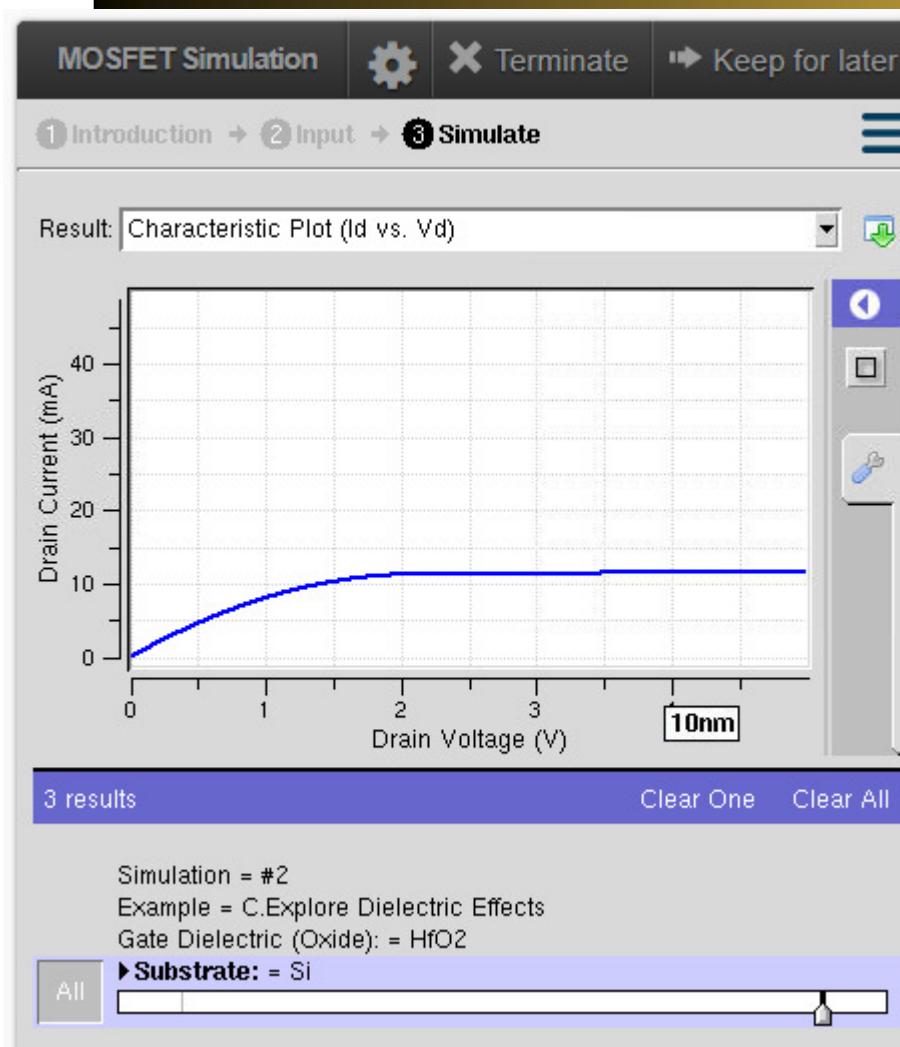
# Putting it all together



MOSFET Simulation Tools:

<https://nanohub.org/tools/mosfet>  
<https://nanohub.org/tools/mosfetsat>

# Comparing Ge with Si



# summary

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- The MOS capacitor is the foundation for MOS field effect transistors (MOSFETs), characterized by many device metrics
- MOSFETs differs from MOSCAPs in that the field from the S/D contacts now causes current flow – can be understood via band diagrams
- Two regimes: diffusion-dominated subthreshold and drift-dominated super-threshold, define the key  $I_D$ - $V_D$ - $V_G$  characteristics of a MOSFET
- Short channels and variability are serious concerns for MOSFET scaling, but strained lattices can help address this issue → effective channel lengths below 15 nm

# New equations on equation sheet

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MOS capacitors:

$$W = \sqrt{\frac{2K_S\epsilon_o\phi_s}{qN_A}} \text{ cm} \quad \epsilon_s = \sqrt{\frac{2qN_A\phi_s}{K_S\epsilon_o}} \frac{\text{V}}{\text{cm}}$$

$$Q_B = -qN_A W(\phi_s) = -\sqrt{2qK_S\epsilon_o N_A \phi_s} \frac{\text{C}}{\text{cm}^2}$$

$$V_G = V_{FB} + \phi_s + \Delta\phi_{ox} = V_{FB} + \phi_s - \frac{Q_s(\phi_s)}{C_{ox}}$$

$$C_{ox} = K_o \epsilon_o / x_o \quad V_{FB} = \Phi_{ms}/q - Q_F/C_{ox}$$

$$C = C_{ox} / \left[ 1 + \frac{K_o W(\phi_s)}{K_S x_o} \right]$$

$$V_T = -Q_B(2\phi_F)/C_{ox} + 2\phi_F \quad Q_n = -C_{ox}(V_G - V_T)$$

# New equations on equation sheet

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MOSFETs:

$$I_D = -WQ_n(y=0)\langle v_y(y=0) \rangle$$

$$I_D = \frac{W}{L}\mu_n C_{ox}(V_{GS} - V_T)V_{DS} \quad I_D = WC_{ox}v_{sat}(V_{GS} - V_T)$$

**Square Law** (for  $V_{GS} \geq V_T$ ):

$$I_D = \begin{cases} \frac{W}{L}\mu_n C_{ox}[(V_{GS} - V_T)V_{DS} - V_{DS}^2/2], & 0 \leq V_{DS} \leq V_{GS} - V_T \\ \frac{W}{2L}\mu_n C_{ox}(V_{GS} - V_T)^2, & V_{DS} \geq V_{GS} - V_T \end{cases}$$

# Review Questions

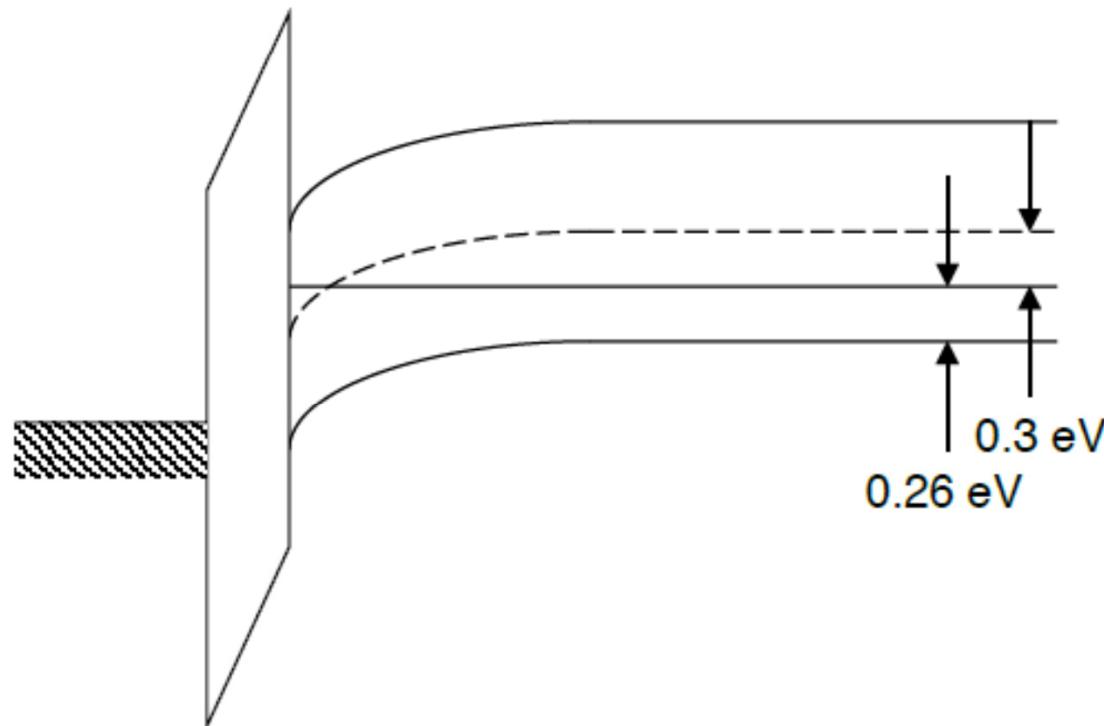
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- 1) Why is the small signal conductance and diffusion capacitance absent for MOS capacitors?
- 2) What is the expression for inversion capacitance? Why isn't there inversion capacitance in a diode?
- 3) What is the difference between flatband voltage vs. threshold voltage?
- 4) When would you use deep depletion formula vs. small signal formula?
- 5) Explain why there is a difference between low frequency response vs. high-frequency response for a MOS-C, but there is no such distinction for MOSFET.

# Example Free Response Question

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5. An MOS capacitor is biased at the threshold of inversion, as shown in the band diagram below. You may assume that no inversion layer charge is present, and that the structure is “ideal” as defined in class. (The sketch is not drawn exactly to scale. Do not attempt to answer the questions below by “measuring” the diagram.)



# Example Free Response Question

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a. What is the surface potential?

# Example Free Response Question

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b. What is the substrate doping?

# Example Free Response Question

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c. What is the semiconductor depletion width?

# Example Free Response Question 2

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A silicon p-type MOS capacitor is maintained in the dark at room temperature. Substrate doping is  $10^{17} \text{ cm}^{-3}$  and the oxide thickness is 20 nm. Assuming it is ‘ideal’, calculate the threshold voltage.